

CEPC Silicon Tracker

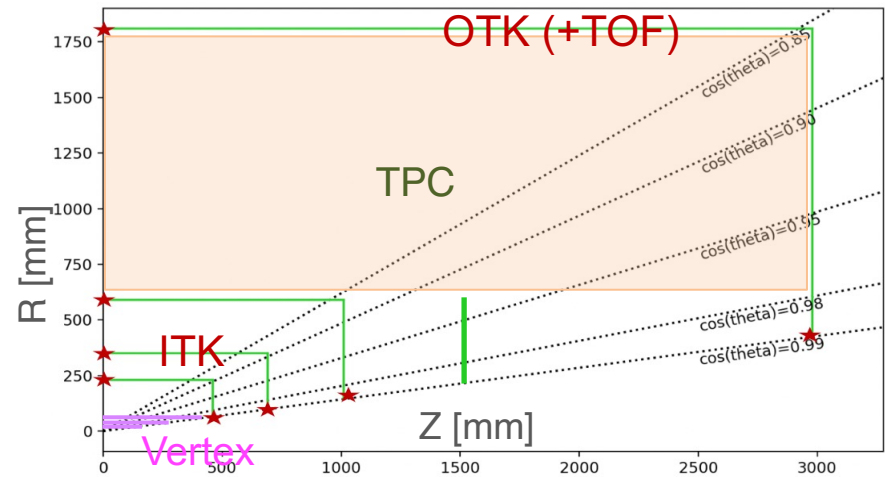
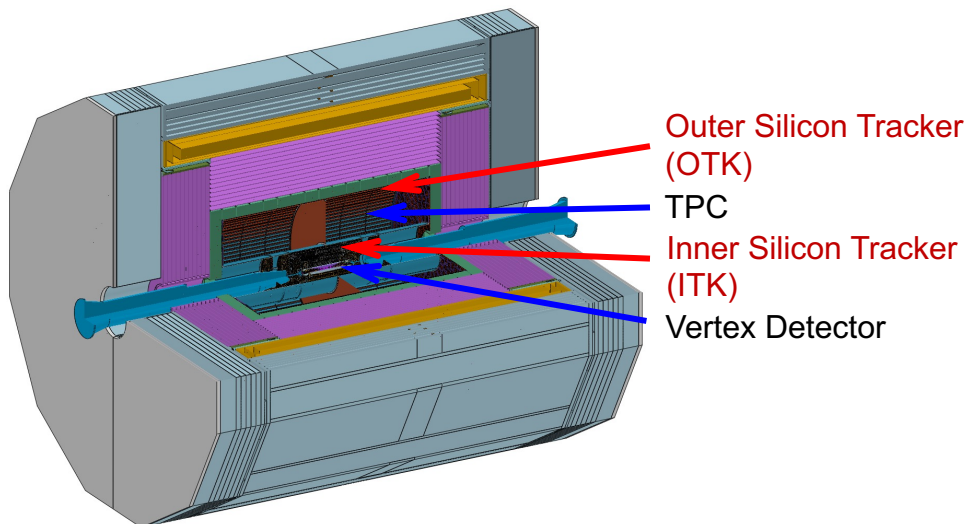
Qi Yan on behalf of the Silicon Tracker Group

CEPC Day, Jan 24, 2025, IHEP

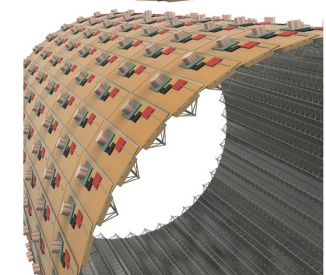
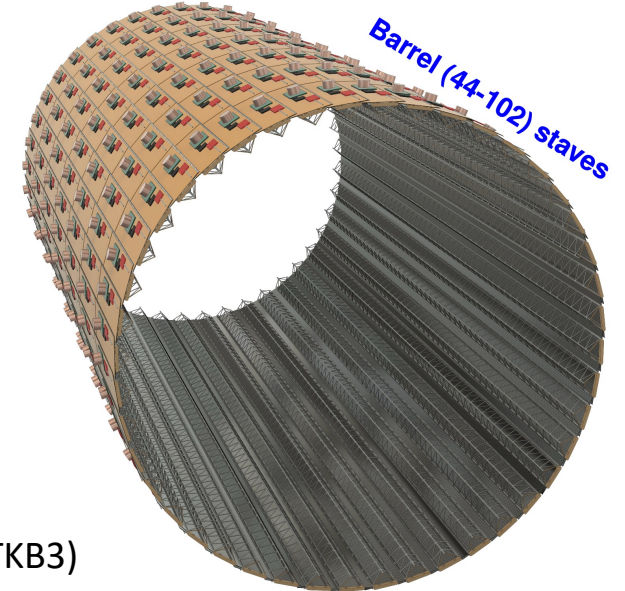
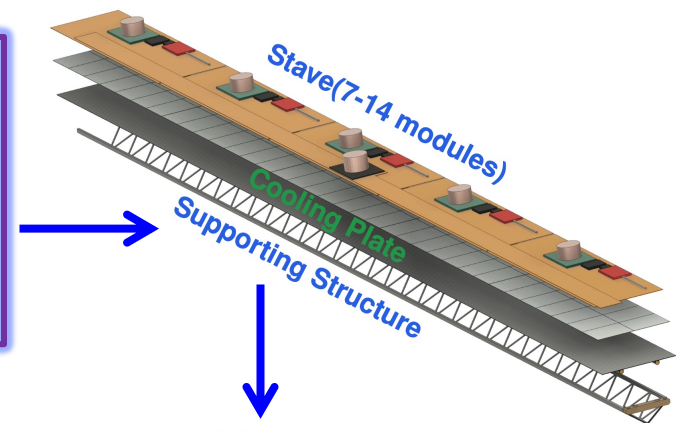
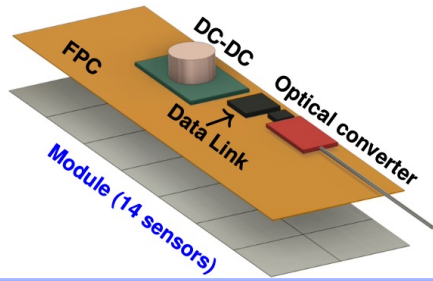
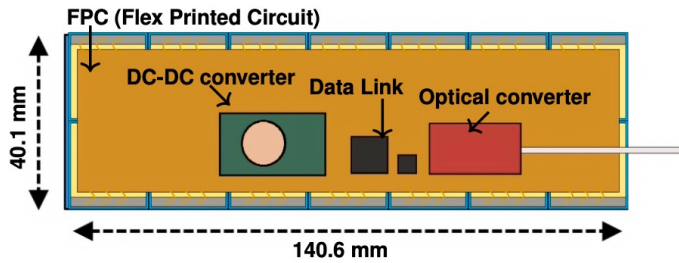
Overview of CEPC Silicon Tracker

We have developed a comprehensive design for the CEPC Silicon Tracker, incorporating many unique design features compared to existing experiments.

In this presentation, I will give a complete overview of the CEPC Silicon Tracker.



CEPC ITK Design: Barrels with HVCMOS Pixels



HVCMOS pixel sensor:

- Sensor size: 20 mm × 20 mm (active area of 17.4 mm × 19.2 mm)
- Array size: 512 rows × 128 columns
- Pixel size: 34 μm × 150 μm (spatial resolution: 8 μm × 40 μm)
- Time resolution: 3-5 ns
- Power consumption: ~200 mW/cm²

Module:

- 14 sensors (2 rows × 7 columns)
- Sensor gap: 100 μm
- Module dimensions: 140.6 mm × 40.1 mm

Stave:

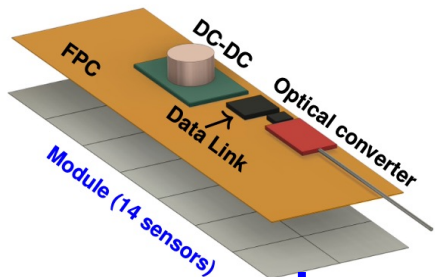
- Module gap: 300 μm
- Length: 986.6 mm (ITKB1), 1,409.6 mm (ITKB2), and 1973.2 mm (ITKB3)

Barrel radii: 235 mm (ITKB1), 345 mm (ITKB2), and 555.6 mm (ITKB3)

Information about staves, modules, and sensors used for 3 ITK barrels construction

Barrel	Number of staves	Modules per stave	Sensors per module	Total number of sensors	Sensor area [m ²]
ITKB1	44	7	14	4312	1.72
ITKB2	64	10	14	8960	3.58
ITKB3	102	14	14	19992	8.00
Total	210			33264	13.31

CEPC ITK Design: Endcaps with HVCMOS Pixels

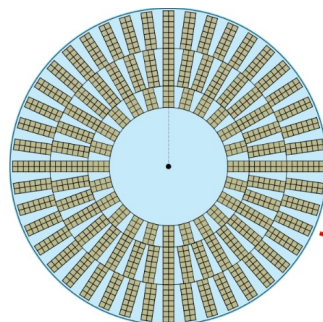


Module:

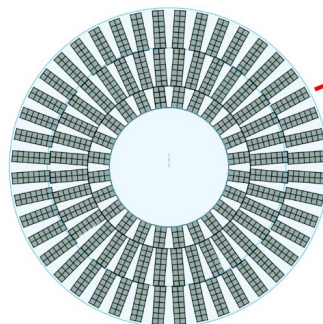
- 3 types of modules: 8, 12, and 14 sensors for all 4 ITK endcaps

Endcap active area radii:

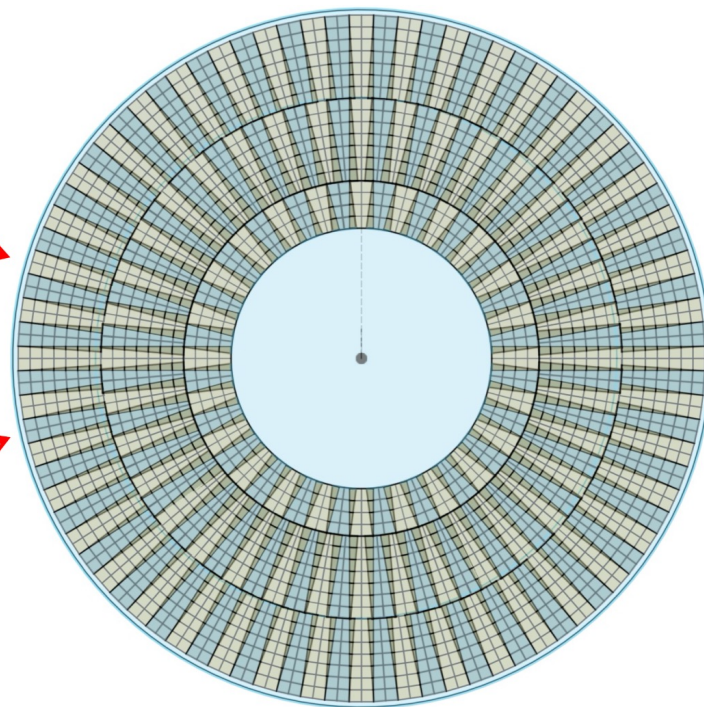
- $81.5 \text{ mm} < r < 242.5 \text{ mm}$ (ITKE1), $110.5 \text{ mm} < r < 352.3 \text{ mm}$ (ITKE2), $163 \text{ mm} < r < 564 \text{ mm}$ (ITKE3), and $223 \text{ mm} < r < 564 \text{ mm}$ (ITKE4)



Front view of endcap



Back view of endcap

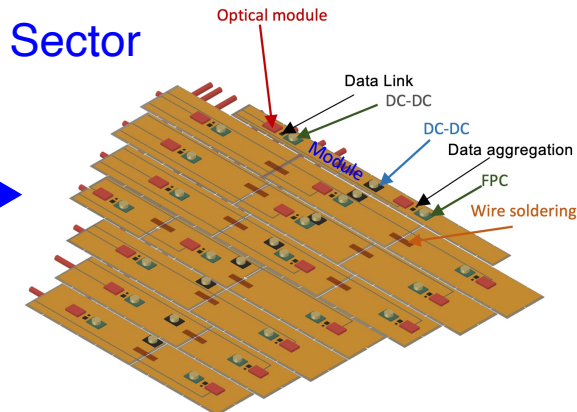
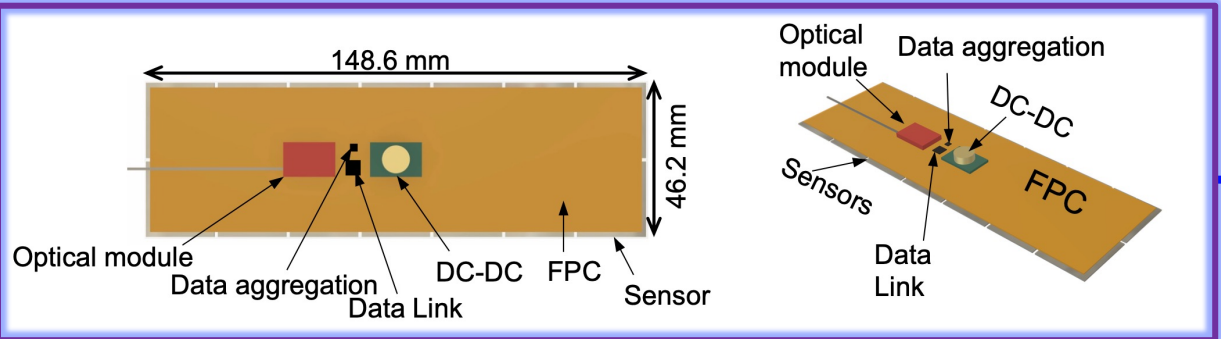


Perspective view of full endcap

The Module and Sensor Layout of a Single Face of Each ITK Endcap

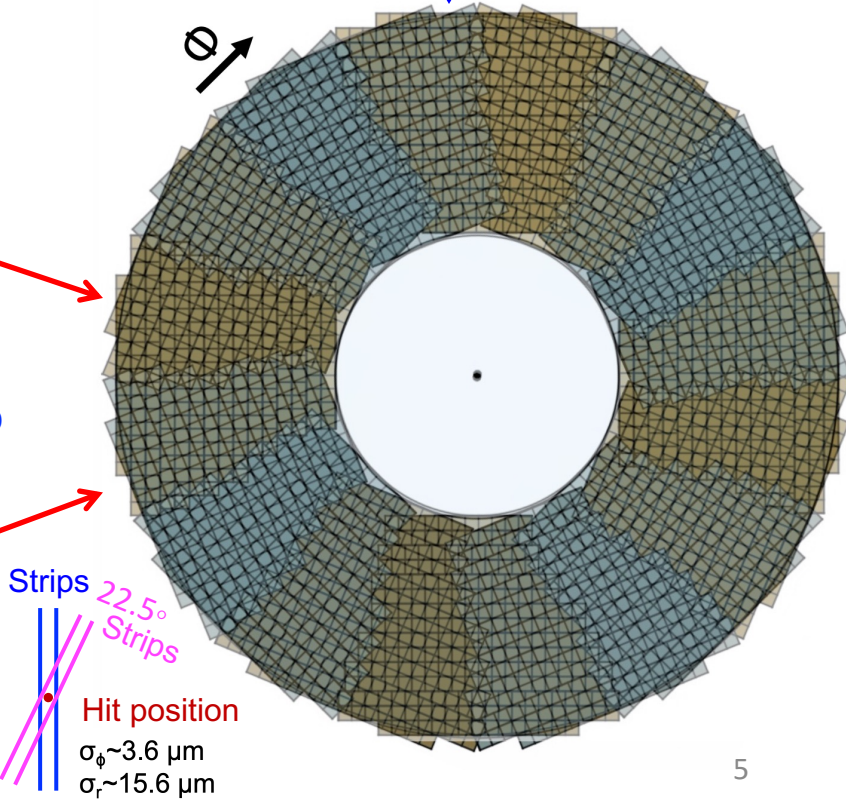
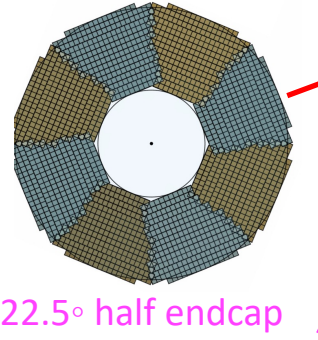
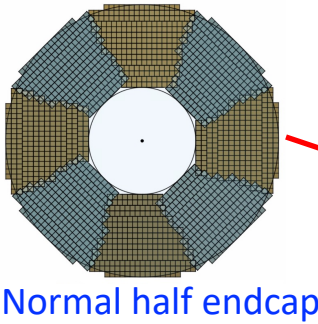
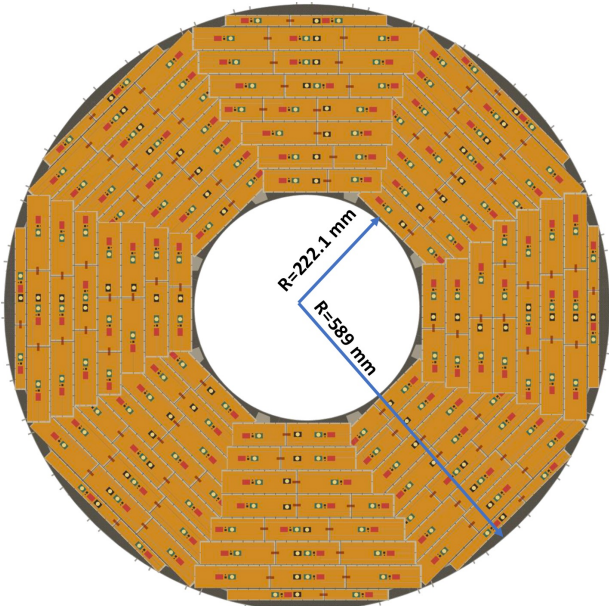
Endcap	Number of module rings	Number of modules per module ring	Number of sensors per module	Total sensors
ITKE1	2	13,20	8,8	264
ITKE2	2	16,24,28	8,8,8	544
ITKE3	3	24,36,44	12,14,14	1408
ITKE4	3	24,36,44	8,12,14	1312
Total				3528

CEPC ITK Design: Endcaps with CMOS Strips (Alternative)

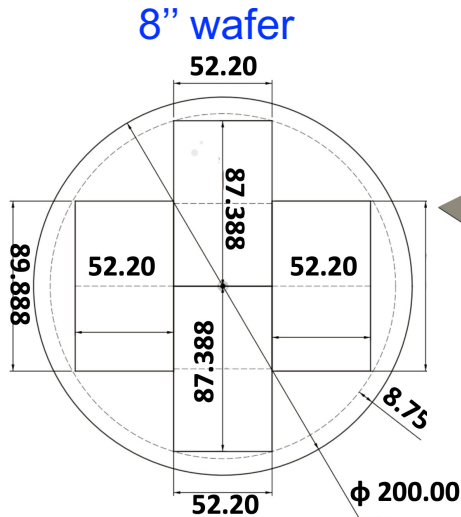


CMOS Strip Chip/Sensor (CSC) for CEPC:

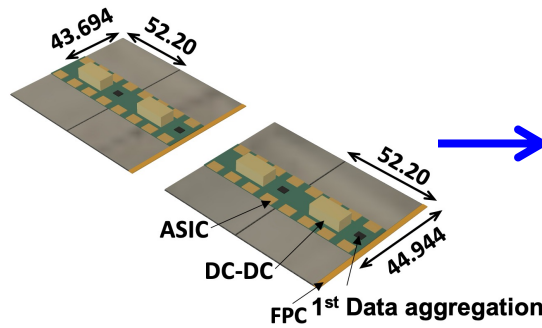
- Chip size: 21 mm × 23 mm
- Strip number per chip: 1024
- Strip pitch size: 20 μm (spatial resolution 5 μm)
- Time resolution: 3-5 ns
- Power consumption: ~80 mW/cm



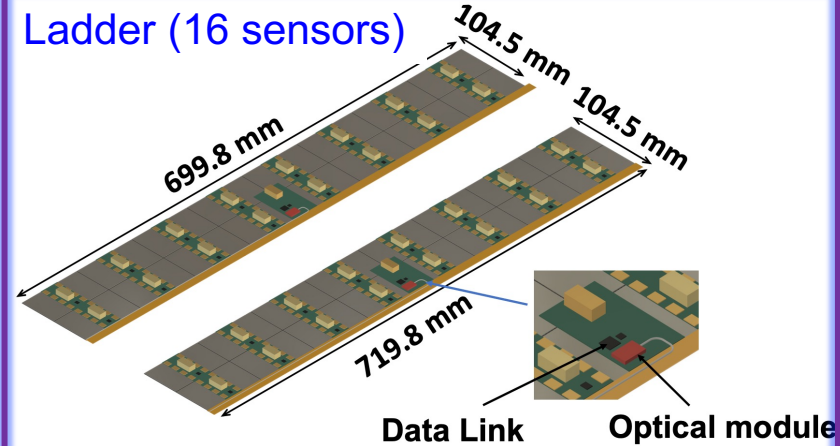
CEPC OTK Barrel Design with AC-LGAD Strips



Module (2 sensors)



Ladder (16 sensors)



AC-LGAD sensor:

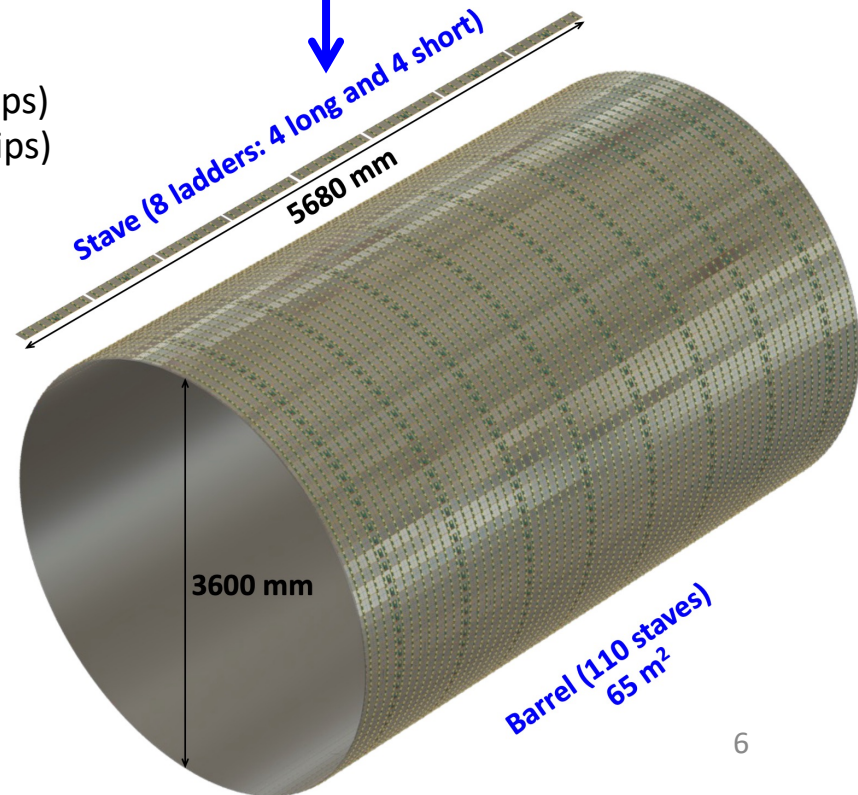
- Sensor size: 87.388 mm × 52.20 mm (2 sets of strips)
89.888 mm × 52.20 mm (2 sets of strips)
- Strip length: 43.644 mm or 44.894 mm
- Strip number: 512 × 2
- Strip pitch: 100 μm
- Time resolution: 50 ps
- Power consumption: 300 mW/cm²

Module: 2 sensors (16 readout ASICs with 128-channels)

Ladder:

- 8 modules (16 sensors)
- Length: 699.8 mm or 719.8 mm

Stave: 8 ladders (4 short+4 long)

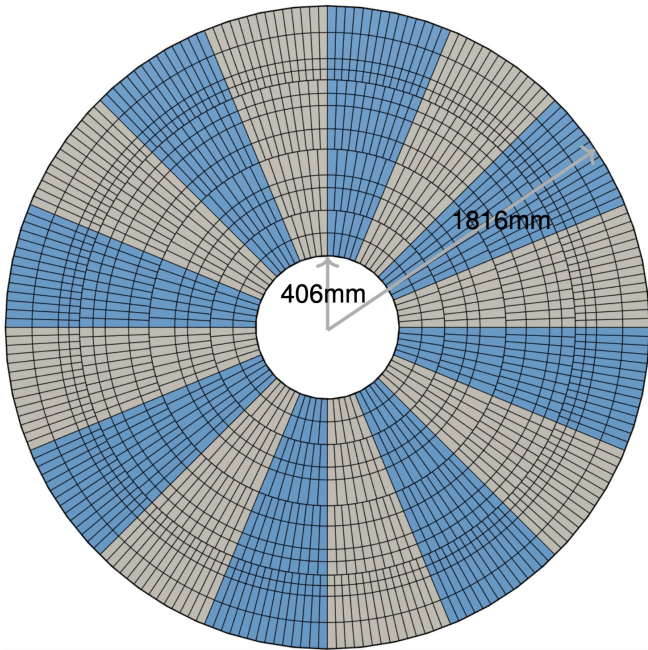


CEPC OTK Endcap Design with AC-LGAD Strips

Endcap (16 sectors, 10 m²)

1/16 Sector

Sensor: 8'' wafer (group C sensors)

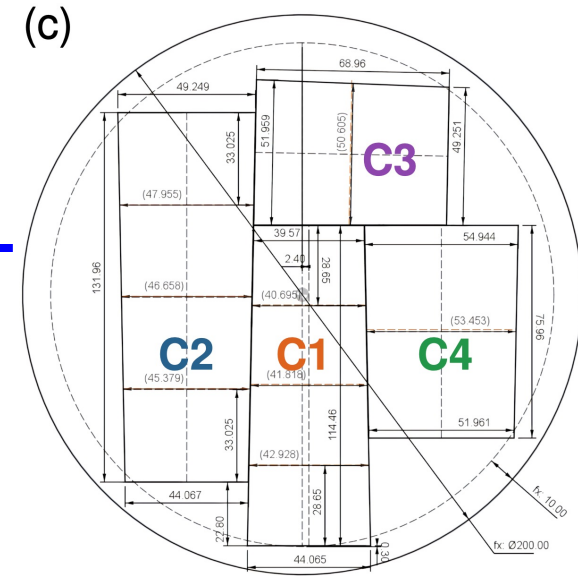
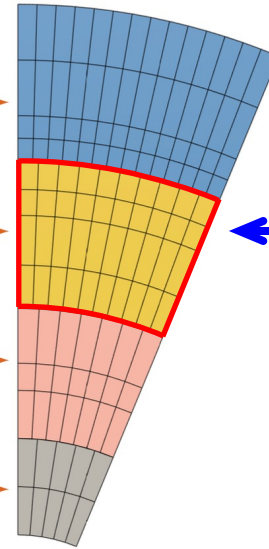


Group D:
1400mm-1816mm

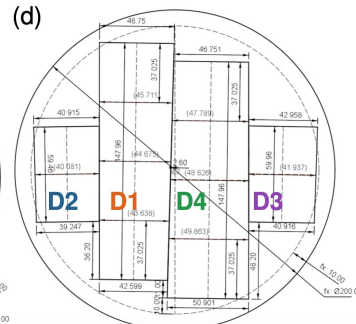
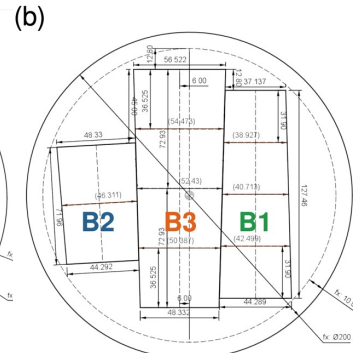
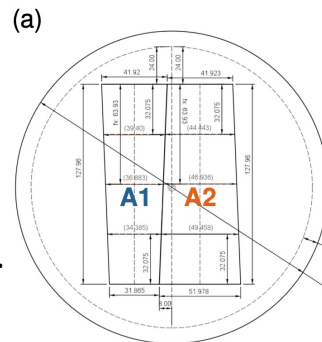
Group C:
1008mm-1400mm

Group B:
662mm-1008mm

Group A:
406mm-662mm



- OTK endcap consists of 13 rings, arranged into 4 groups.
- Each group contains 2-4 types of trapezoid sensors, dicing from one 8'' silicon wafer.
- Each group of sensors is aligned to a 1/16 sector.
- The long sensor contains 4 sets of short strips while short sensor contains 2 sets of short strips.
 - Strip pitch : 80.7-113.8 μm
 - Strip length : 28.38-37.61 mm



8'' wafer (group A, B, D sensors)

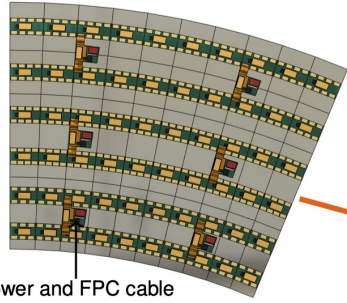
Maximize the use of silicon wafers and facilitate detector assembly.

CEPC OTK Endcap Design with AC-LGAD Strips (2)

Group C sensors:

1/16 Sector

Endcap (16 sectors)



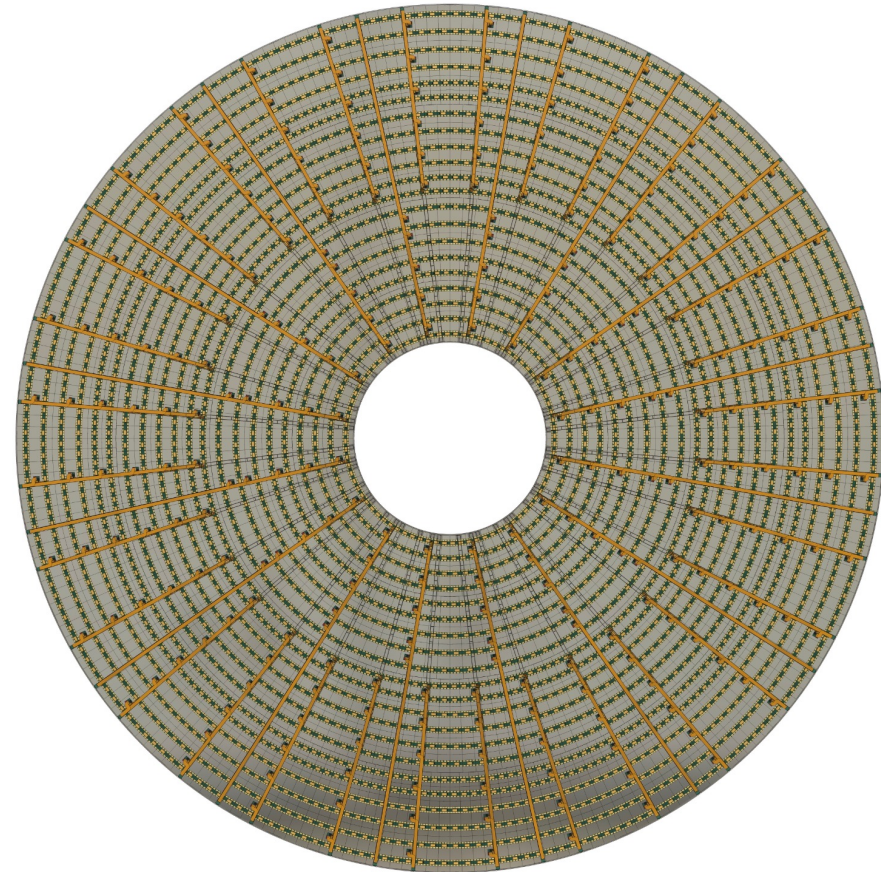
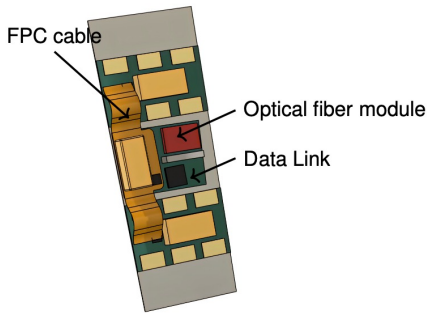
Group D:

Group C:

Group B:

Group A:

r: 406mm - 1816mm



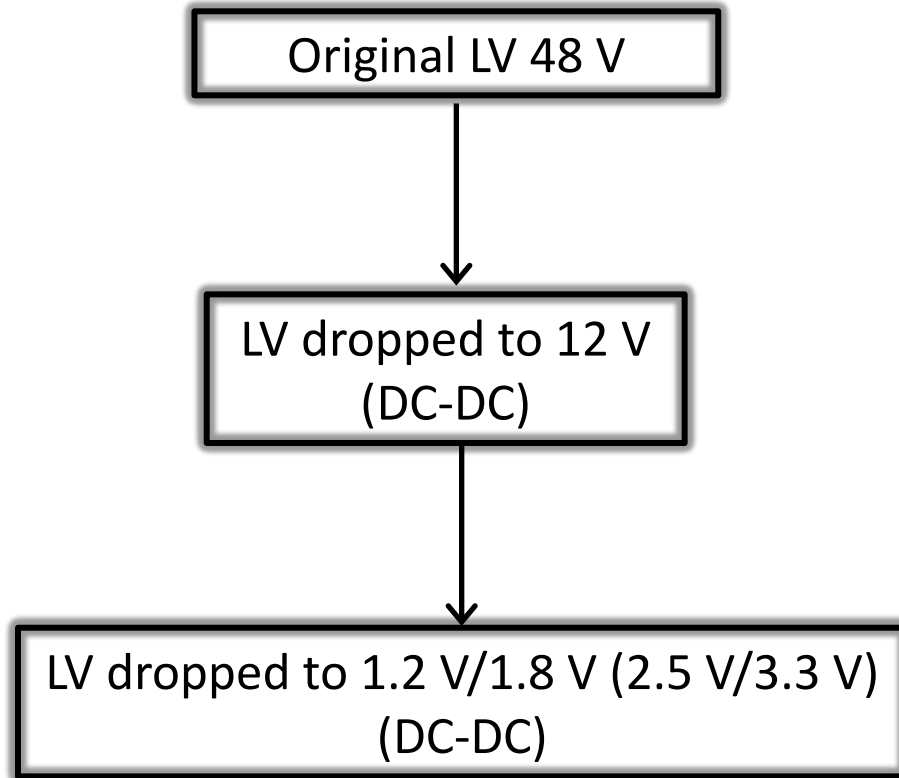
OTK Endcap Trapezoidal Sensor Strip Parameters

Sensor type	Number of strip sets	Number of strips per set	Strip pitch [μm]	Strip length [mm]
A1	4	384	81.5-107.6	31.755
A2	4	512	80.7-100.3	31.755
B1	4	384	95.1-113.8	31.630
B2	2	512	85.3-93.2	35.610
B3	4	512	93.2-109.2	36.255
C1	4	384	101.5-113.2	28.380
C2	4	512	84.9-95.0	32.755
C3	2	512	95.0-100.3	34.110
C4	2	512	100.3-106.1	37.610
D1	2	384	100.6-105.0	29.360
D2	2	384	105.0-109.4	29.610
D3	4	512	82.0-90.1	36.755
D4	4	512	90.1-98.2	36.755

Sensors and Silicon Wafers Usage per OTK Endcap

Mask	A		B			C				D			
	A1	A2	B1	B2	B3	C1	C2	C3	C4	D1	D2	D3	D4
Number of sensors	80	80	112	112	112	160	160	160	160	224	224	224	224
Number of wafers	80		112			160				224			

Silicon Tracker Power Cabling Scheme



Power Rail for ITK Barrel Stave

Module (14 sensor) FPC

3: DC-DC:
LV input 12 V
LV output 1.2 V (2.5V)

Power Bus FPC

2: DC-DC:
LV input 48 V
LV output 12 V

1: Power Bus:
HV input 150 V
LV input 48 V

ITKB1: 7 modules per stave (986.6 mm)
ITKB2: 10 modules per stave (1,409.6 mm)
ITKB3: 14 modules per stave (1,973.2 mm)

The staves of ITKB2 and ITKB3 use 2 Power Buses, each serving 5 or 7 modules from one end.

Power requirement per Power Bus:
5-module: ~60 W
7-module: ~84 W

For the 7 modules, the currents are:
48V: 1.75 A
12V (with 2 lanes): 3.5 A

Qi Yan, Yihan Zhang, Shoudong
Luo, Xiongbo Yan

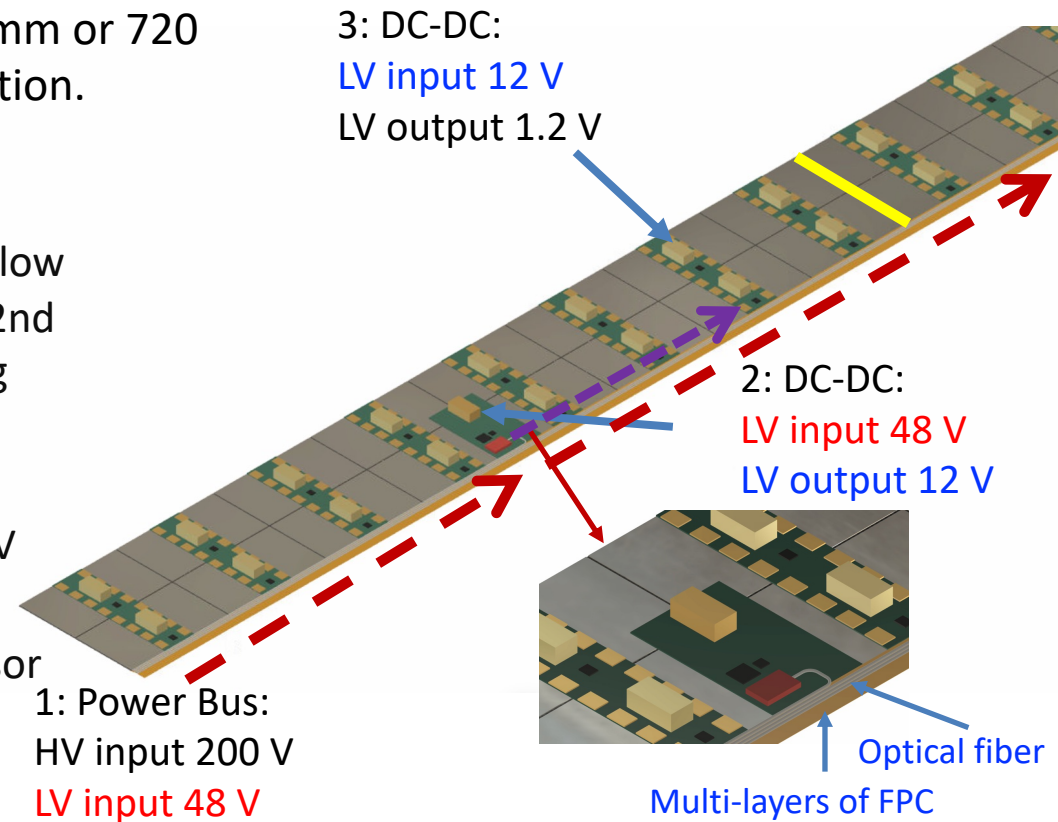
Power Rail for OTK Barrel Stave

Qi Yan, Yihan Zhang, Shoudong Luo, Xiongbo Yan

One OTK stave consists of 8 ladders (700 mm or 720 mm), with 4 ladders read out in one direction.

OTK Voltage Transmission

- The high voltage (HV, 200 V) and original low voltage (LV, 48 V) are transmitted to the 2nd data aggregation boards through the long power bus FPC (Stave FPC).
- The DC-DC converters in the 2nd data aggregation boards step down the 48 V LV input to 12 V.
- The 12 V LV, along with 200 V HV for sensor biasing, is distributed to all modules via shorter ladder FPC.





Data Link:

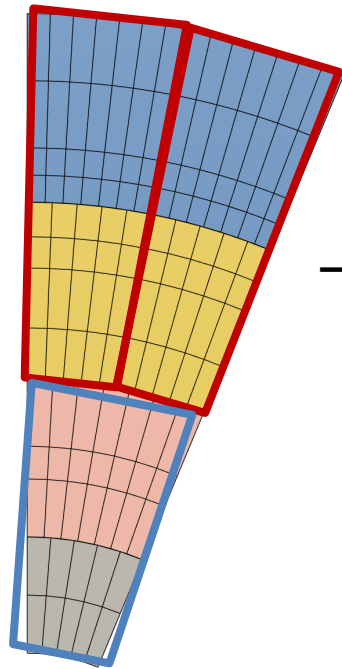
- Data output, clock and commands inputs are transmitted between sensor modules and optical module on the secondary data aggregation board through the ladder FPC.

Power Rail for OTK Endcap (1/16 Sector)

Total power requirement:
1840 W per sector (300 mW/cm^2)

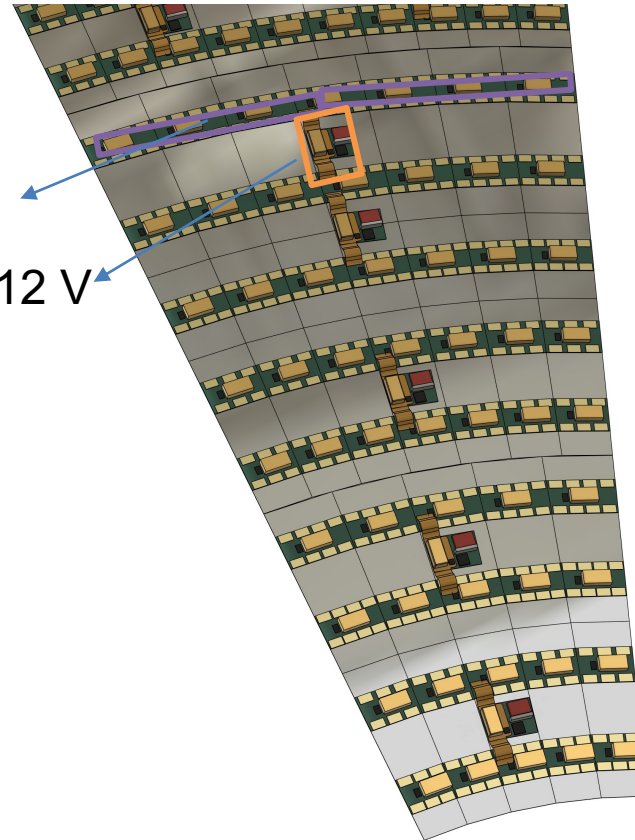
Upper Area:  670 W each
Lower Area:  500 W

Qi Yan, Yihan Zhang,
Shoudong Luo, Xiongbo Yan



一级: 12 V \rightarrow 1.2 V

二级: 48 V \rightarrow 12 V



83.6 W \sim 7A (12 V)

77.2 W

70.1 W

60.8 W

48.3 W

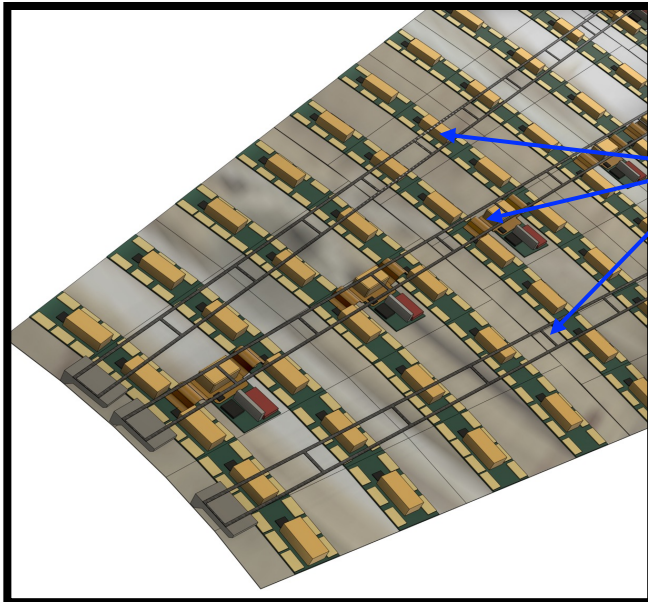
46.8 W

42.2 W

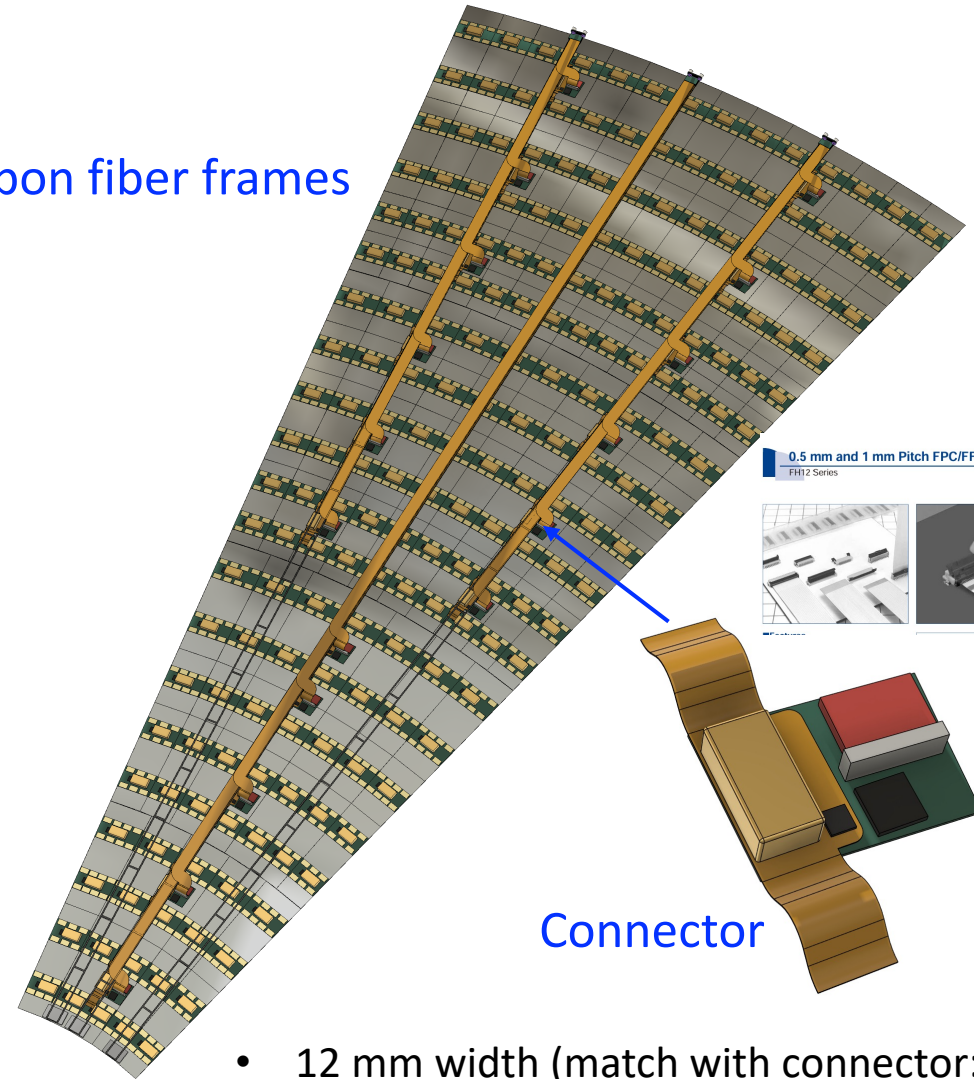
38.9 W

32.1 W

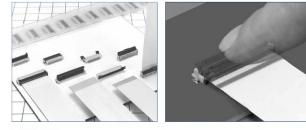
OTK Endcap Power Rail: Power Buses on 3 Frames



Carbon fiber frames



0.5 mm and 1 mm Pitch FPC/FFC Connectors
FH12 Series



Connector

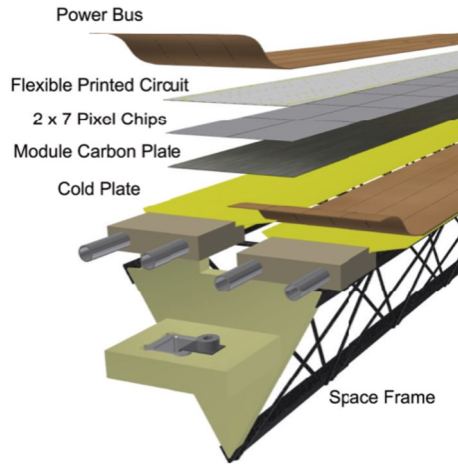
Power Bus transmits: HV (200 V) and LV (48 V)

- 180 μm thick (with metal layer of 25 μm copper or aluminum) is more than sufficient

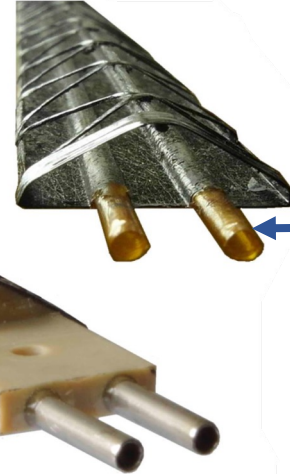
- 12 mm width (match with connector: 24 pins x 0.5 mm pitch)
- Max length: 1,330 mm
- Max power transmission: 4.8 A, 230 W

Improvement of the ITK Stave Support and Cooling Design

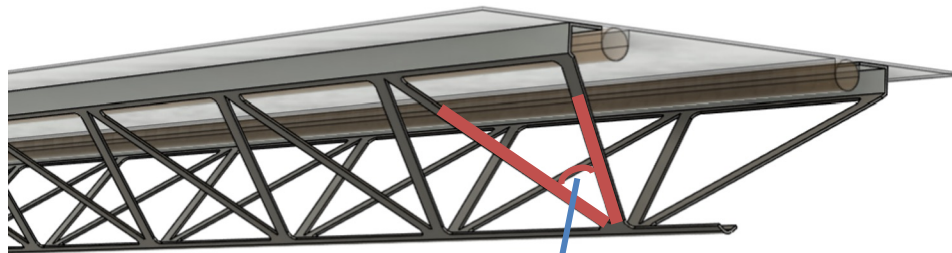
ITS2 Outer barrel stave



ITS2 Inner barrel stave



Qi Yan, Yihan Zhang, Yujie Li, and Quan Ji

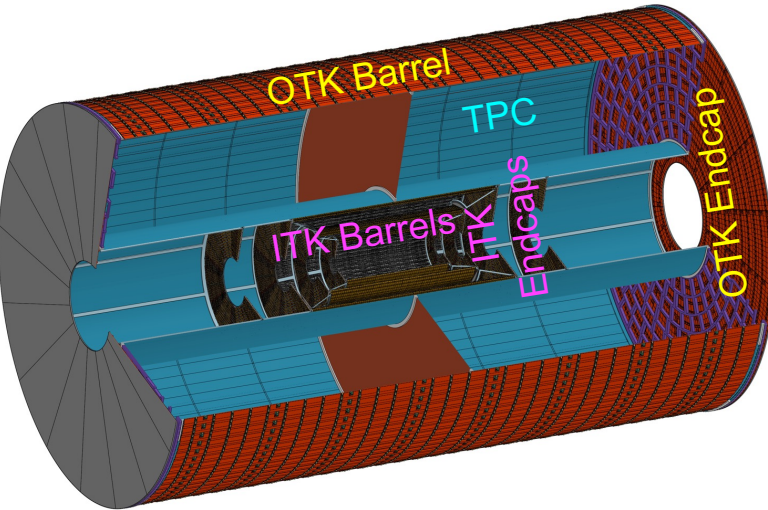


58 - 62 deg

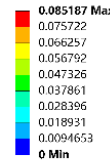


Water with polyimide cooling pipe was used as baseline cooling fluid for the ITK. Polyimide possesses outstanding properties such as low mass, high temperature resistance, corrosion resistance, radiation resistance, and high strength.

ITK Stave Deformation and First Natural Frequency



A: Static Structural
Total Deformation
Type: Total Deformation
Unit: mm
Time: 1

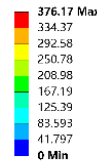


ITKB1 stave deformation

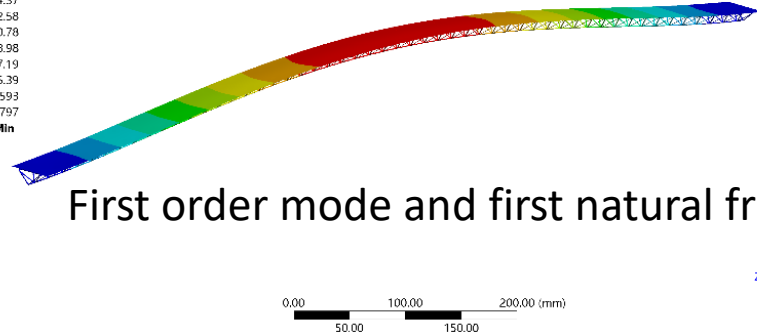


Yujie Li and Quan Ji

Type: Total Deformation
Frequency: 126.17355 Hz
Unit: mm



First order mode and first natural frequency



ITK Stave	ITKB1	ITKB2	ITKB3
Stave length [mm]	987	1410	1974
Maximum sag [μm]	85	289	896
First natural frequency [Hz]	126	69	34

The first natural frequency indicates the frequency at which an external impulse can induce resonance phenomena in the structure, resulting in oscillations of the sensor positions.

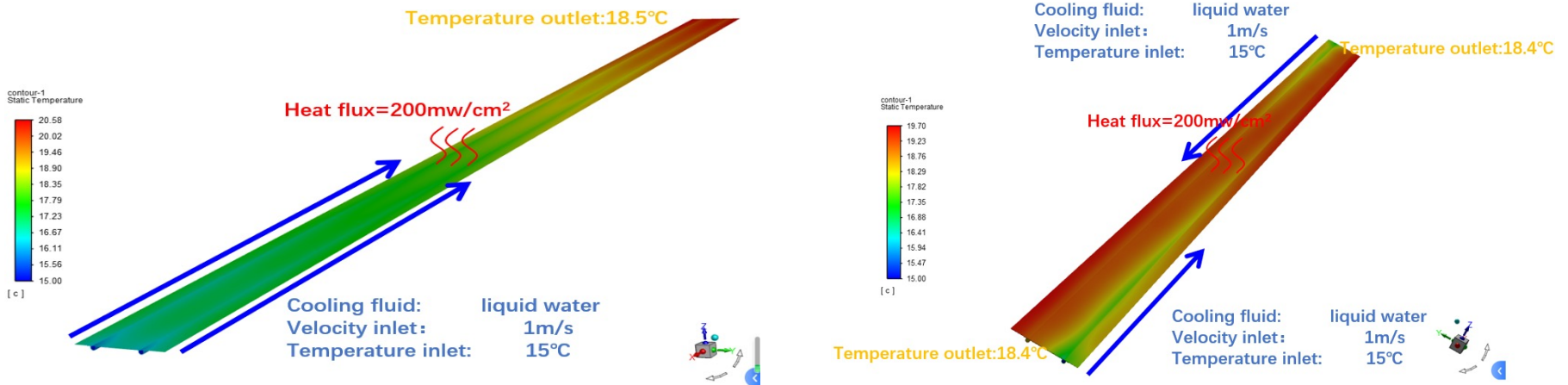
ITK Barrel Stave Thermal Characterisation

The heat generated by ITK sensors with a magnitude of 200 mW/cm^2 . The cooling design should achieve the following:

- The overall sensor operating temperature $<30 \text{ }^\circ\text{C}$.
- The temperature uniformity across a single sensor $<5 \text{ }^\circ\text{C}$.

Yujie Li and Quan Ji

A water cooling fluid structure coupled finite element model was established to study the temperature distribution:



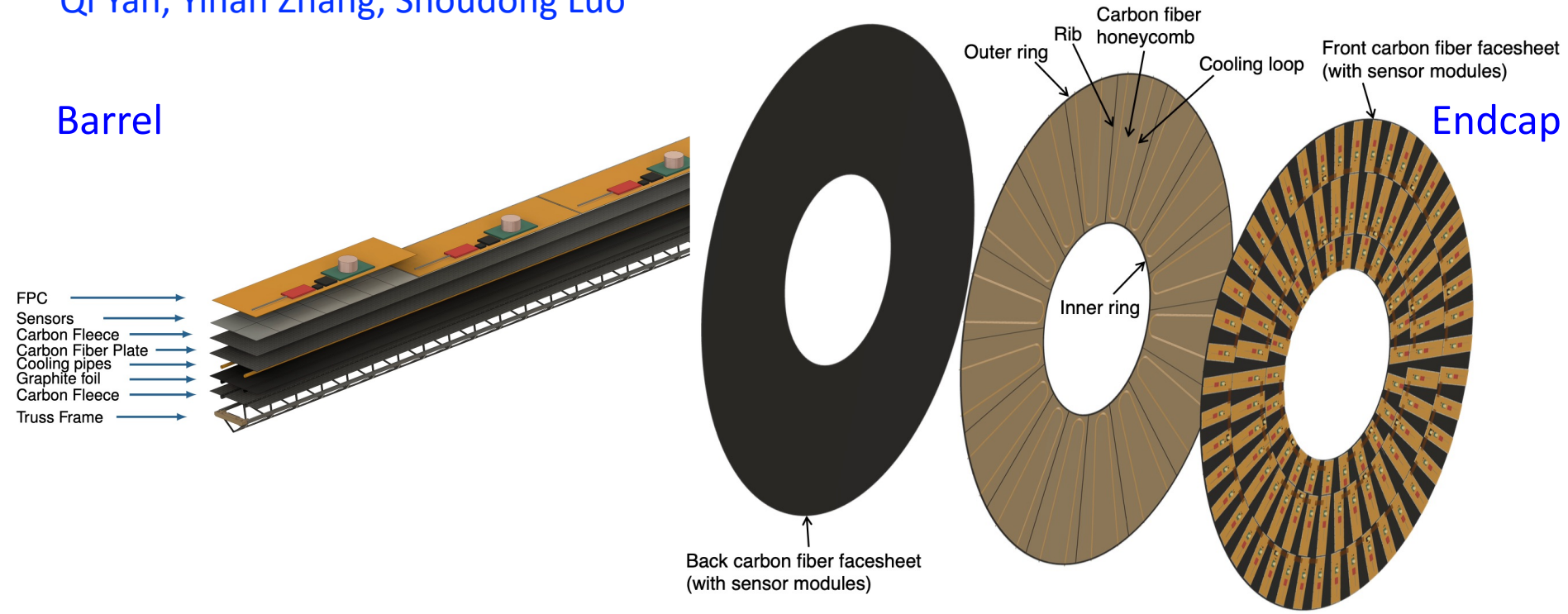
The temperature gradient along the 987 mm length of the stave can be controlled within 5°C . The water cooling meets the detector's requirements.

ITK Mechanical and Cooling Structure Design

Qi Yan, Yihan Zhang, Shoudong Luo

Barrel

Endcap



Estimation of ITK stave material contributions

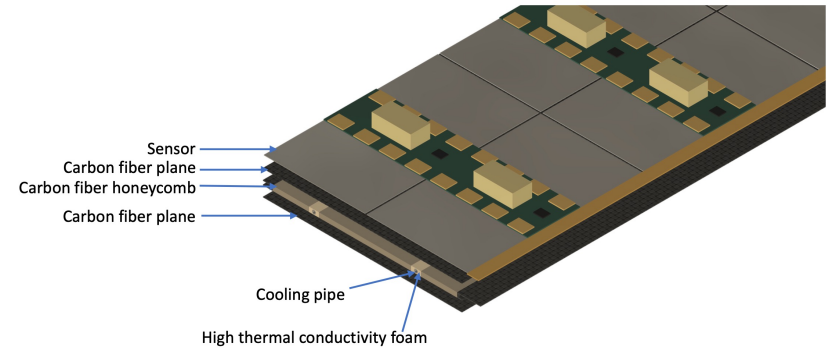
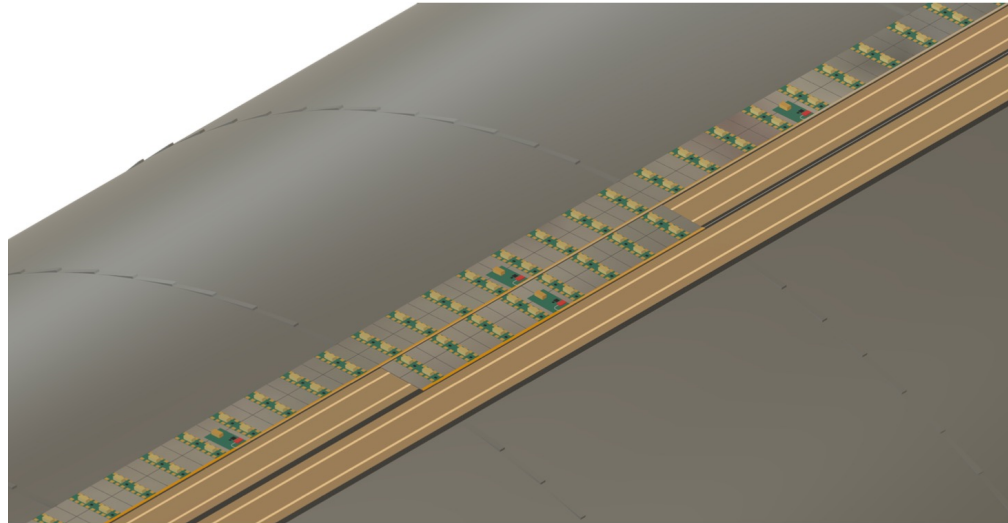
Functional unit	Component	Material	Thickness [μm]	X ₀ [cm]	Radiation Length [% X ₀]
Sensor Module	FPC metal layers	Aluminium	100	8.896	0.112
	FPC Insulating layers	Polyimide	100	28.41	0.035
	Sensor	Silicon	150	9.369	0.160
	Glue		100	44.37	0.023
	Other electronics				0.050
	Cooling Plate	Carbon fleece layers	Carbon fleece	40	106.80
Carbon fiber plate		Carbon fiber	150	26.08	0.057
Cooling tube wall		Polyimide	64	28.41	0.013
Cooling fluid		Water		35.76	0.105
Graphite foil		Graphite	30	26.56	0.011
Glue		Cyanate ester resin	100	44.37	0.023
Truss Frame	Carbon rowing				0.080
Total					0.673

Estimation of ITK HV-CMOS pixel endcap material contributions

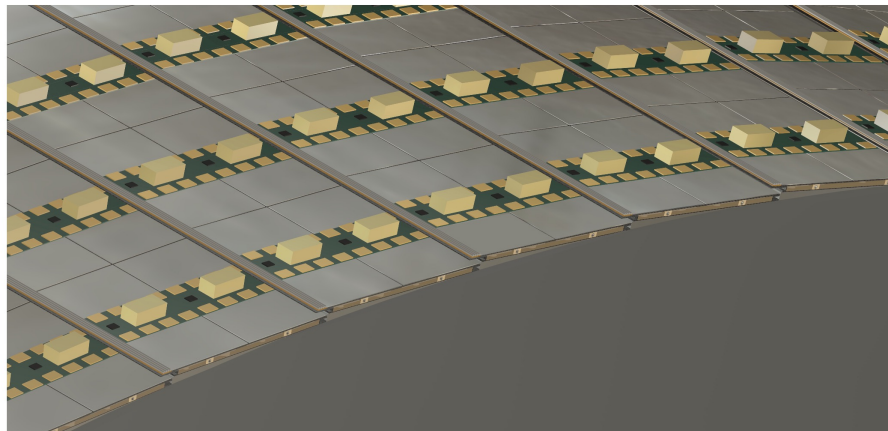
Functional unit	Component	Material	Thickness [μm]	X ₀ [cm]	Radiation Length [% X ₀]
Sensor Module	FPC metal layers	Aluminium	50	8.896	0.056
	FPC Insulating layers	Polyimide	100	28.41	0.035
	Sensor	Silicon	150	9.369	0.160
	Glue		100	44.37	0.023
	Other electronics				0.050
	Structure	Carbon fiber facesheet	Carbon fiber	150	26.08
Cooling tube wall		Titanium		3.560	XXX
Cooling fluid		Water		35.76	XXX
Graphite foam+Honeycomb		Allcomp+Carbon fiber	2000	186	0.108
Carbon fiber facesheet		Carbon fiber	150	26.08	0.057
Glue		Cyanate ester resin	200	44.37	0.045
Total					0.591+XXX

Mechanical and Cooling Structure Design for the OTK Barrel

Qi Yan, Shoudong Luo, Quan Ji



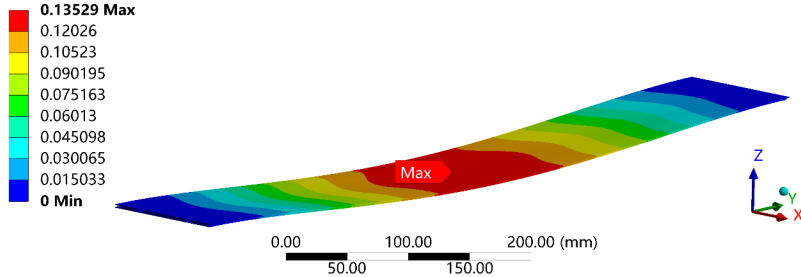
- 1) The TPC outer barrel is made of a carbon fiber cylinder with stepped ramp rings.
- 2) The lower support carbon fiber facesheet, with a carbon fiber honeycomb glued on top, was mounted onto the stepped ramp rings.
- 3) Two cooling pipes (~6 m in length), were then inserted into the gaps of the carbon fiber honeycomb, sealed with high conductivity foam surrounding them.
- 4) 8 ladders were glued on top one by one to enclose stave honeycomb and complete the construction of one stave. Each OTK ladder (~0.7 meters) has its own support, consisting of 16 sensors, electronic components, and a carbon fiber facesheet.



OTK Barrel Structural and Thermal Characterisation

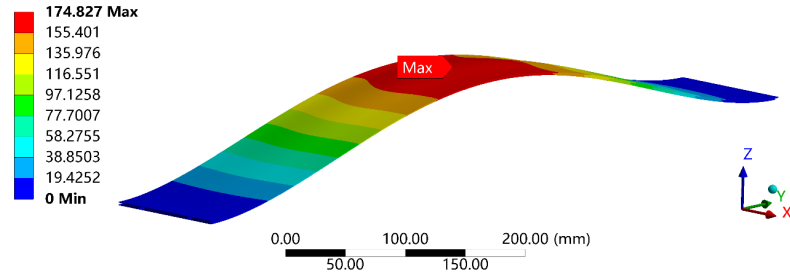
A: Static Structural
 Total Deformation
 Type: Total Deformation
 Unit: mm
 Time: 1

Maximum sag: 0.135 mm



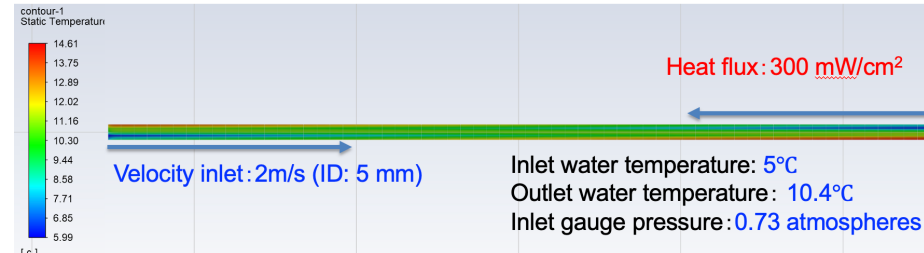
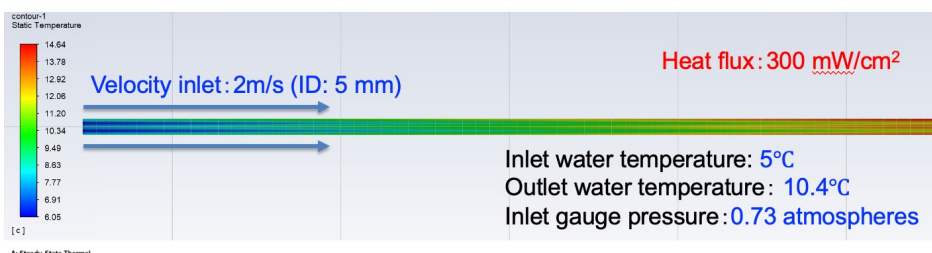
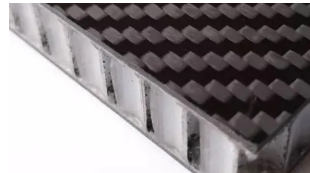
B: Modal
 Total Deformation
 Type: Total Deformation
 Frequency: 76.130848 Hz
 Unit: mm

First natural frequency: 76.1 Hz



Yujie LI and Quan JI

Honeycomb filled with poco foam to increase thermal conductivity



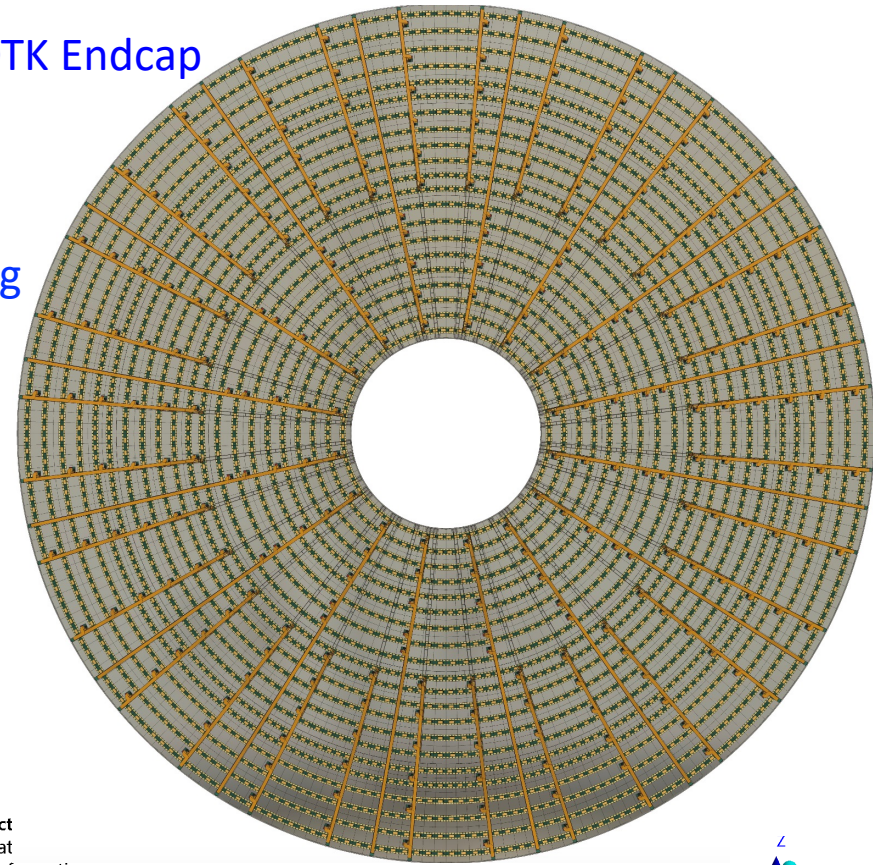
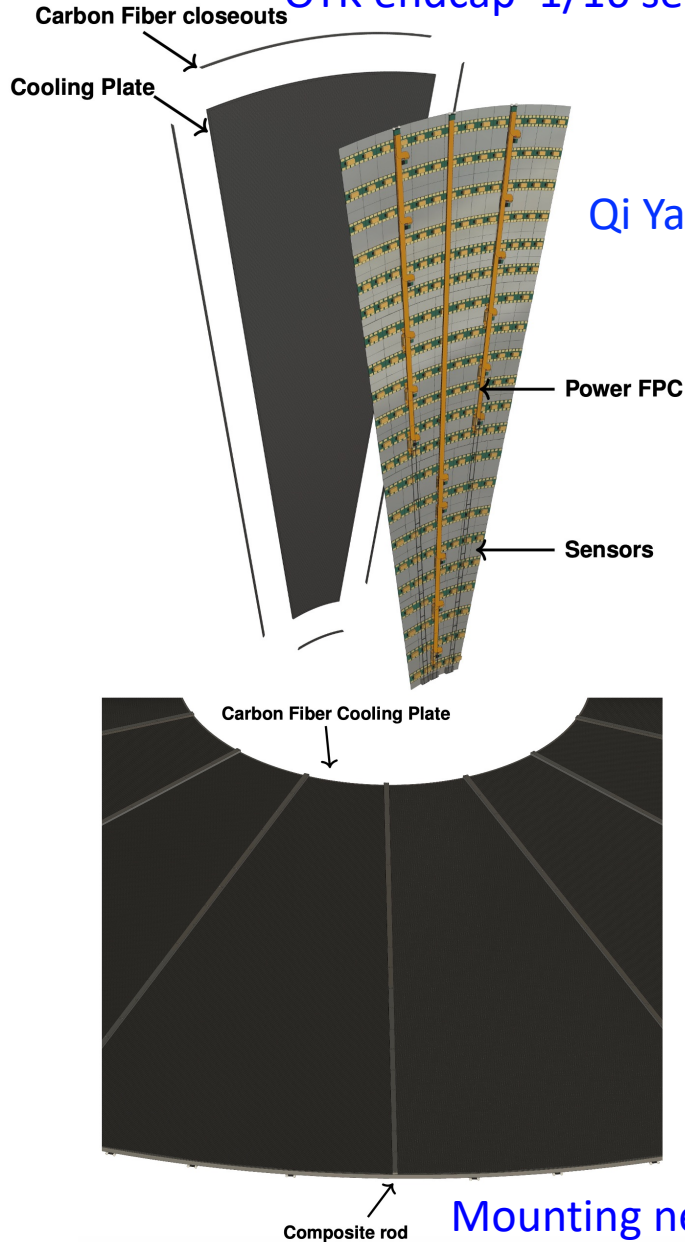
Using a 5 °C and 2 m/s water inlet (ID: 5 mm), the maximum temperature difference across one sensor is <2.9 °C for inlet from one end and <4 °C for inlet from two ends.

Water cooling can meet the thermal requirements for the OTK over ~6 m stave length.

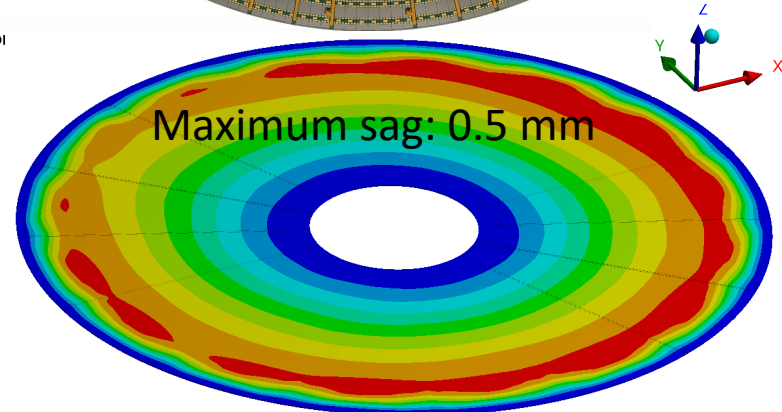
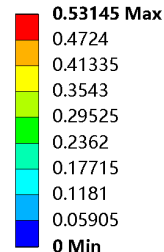
Mechanical and Cooling Design for the OTK Endcap

OTK endcap 1/16 sector

OTK Endcap



D: Static Struct
 Total Deformat
 Type: Total Deformation
 Unit: mm
 Time: 1



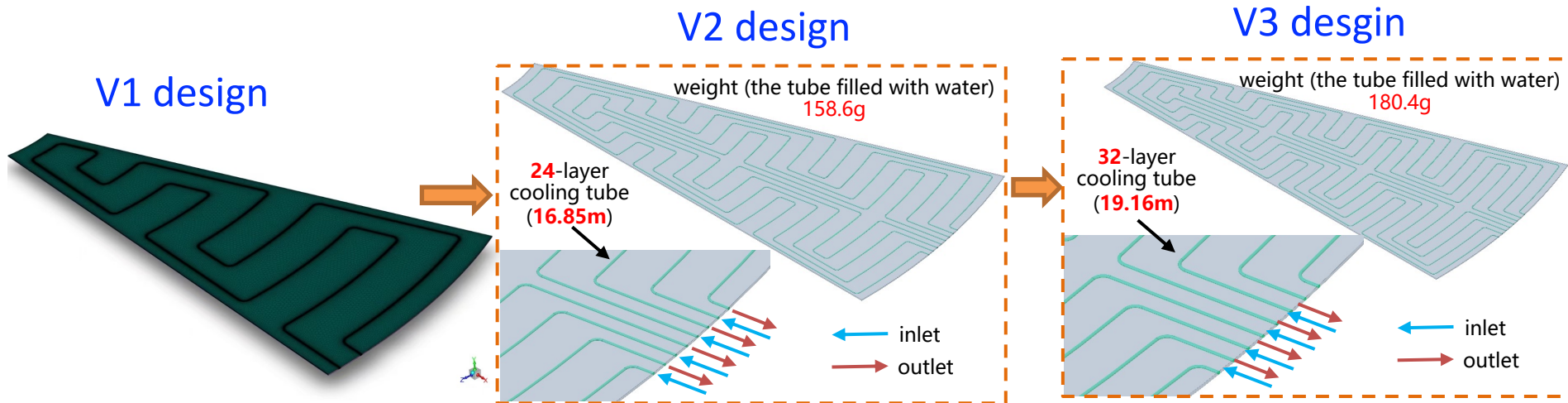
Yujie LI and Quan JI

Cooling Loop Design for the OTK Endcap

A few months ago, Quan Ji, Gang Li, and I visited Zhengzhou University of Light Industry, to explore ways to strengthen CEPC's R&D capabilities in mechanical and thermal systems.

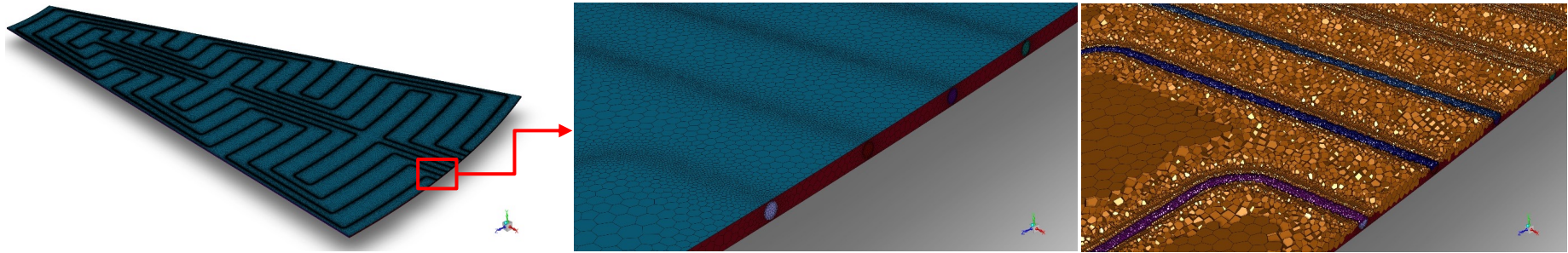
The School of Energy and Power Engineering at Zhengzhou University of Light Industry has extensive experience and a strong focus on thermal system development, including CO₂ cooling. During our visit, we were highly impressed by their expertise in both thermal and mechanical engineering.

On Jan 10, the Dean of the School of Energy and Power Engineering, Professor Xuehong Wu, and his team, visited IHEP in return. They are now actively contributing to the design and analysis of the CEPC thermal system.

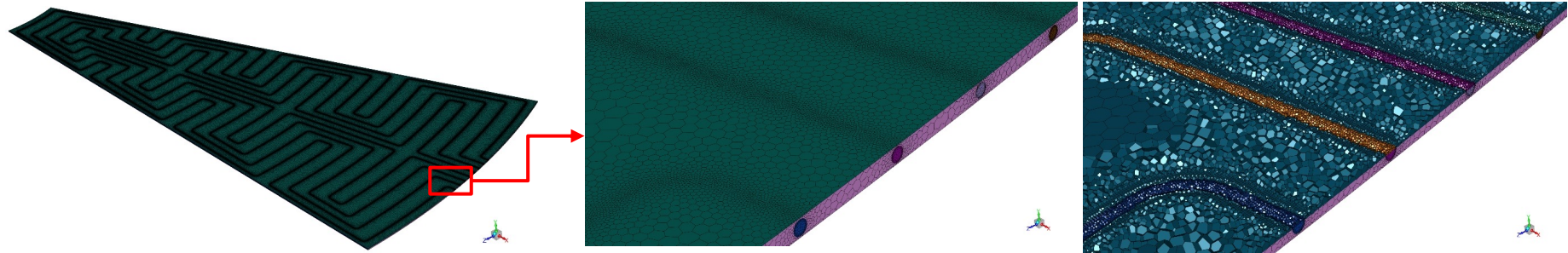


Cooling loops design and thermal analysis for the OTK endcap performed by Zhengzhou University of Light Industry (郑州轻工业大学).

OTK Endcap Thermal Mesh Generation



24-layer cooling tube(16.85m, cell count 9356670, Orthogonal Quality \geq 0.5)



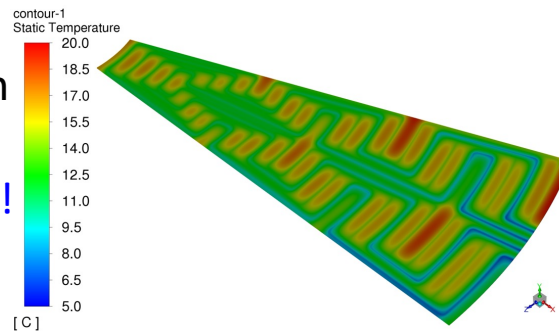
32-layer cooling tube(19.16m, cell count 10645946, Orthogonal Quality \geq 0.5)

- ✓ The **mesh generation** is performed for **two different cooling tube arrangements**, and numerical solutions are obtained using **the finite volume method**.
- ✓ The **cooling performance** of both arrangements is **analyzed** and compared.

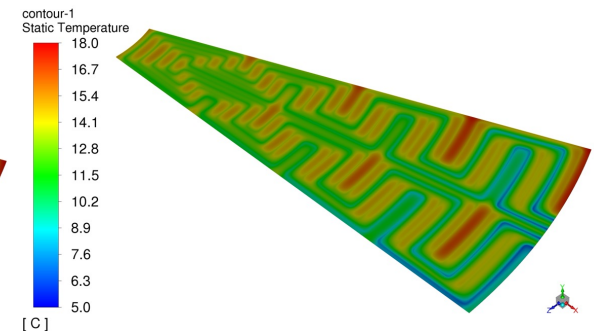
- Cooling tube diameter: 2.6 mm
- Water inlet velocity: 2.5m/s

Continuous optimization is ongoing!

Xuedong Wu, Yong Liu, ...
(郑州轻工业大学)



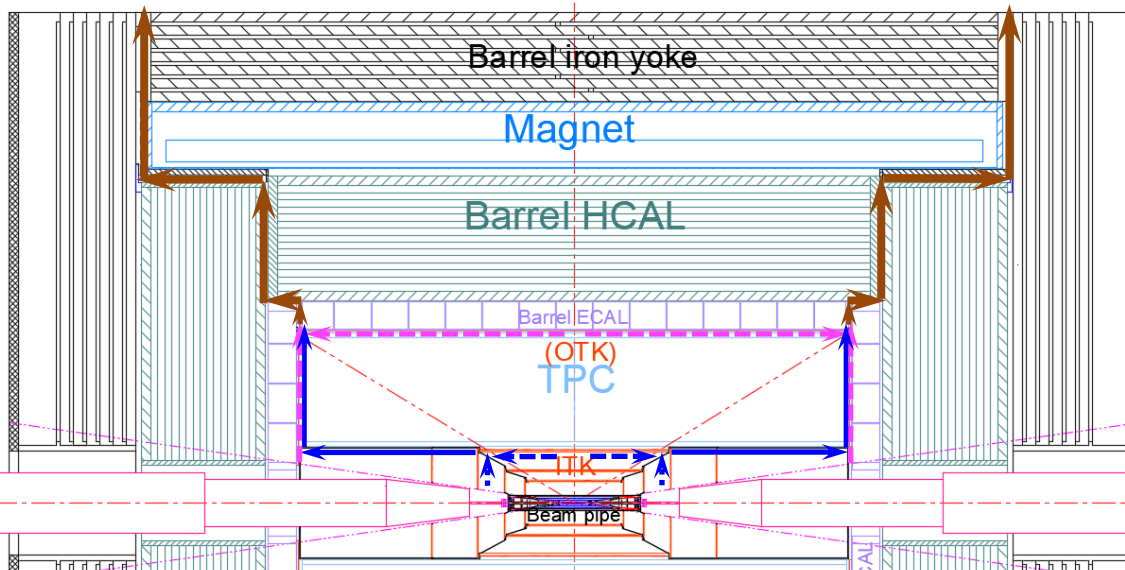
24-layer cooling tube



32-layer cooling tube

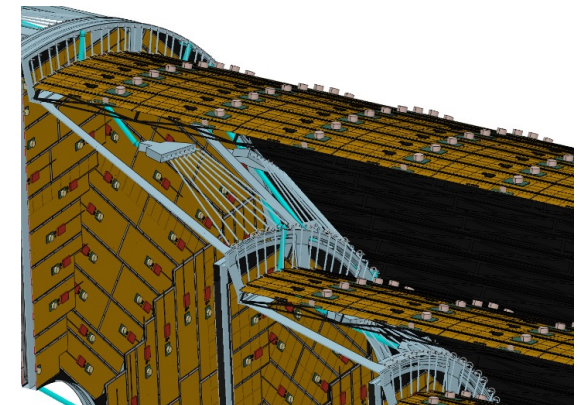
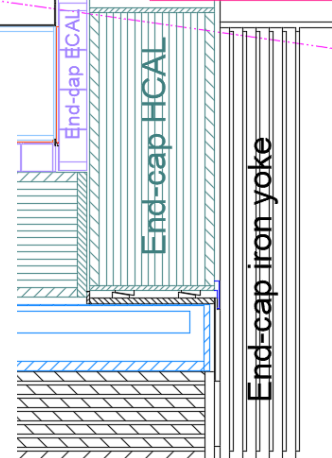
Silicon Tracker Power and Cooling Rail Routing Outward

Qi Yan, Quan Ji, Xiongbo Yan

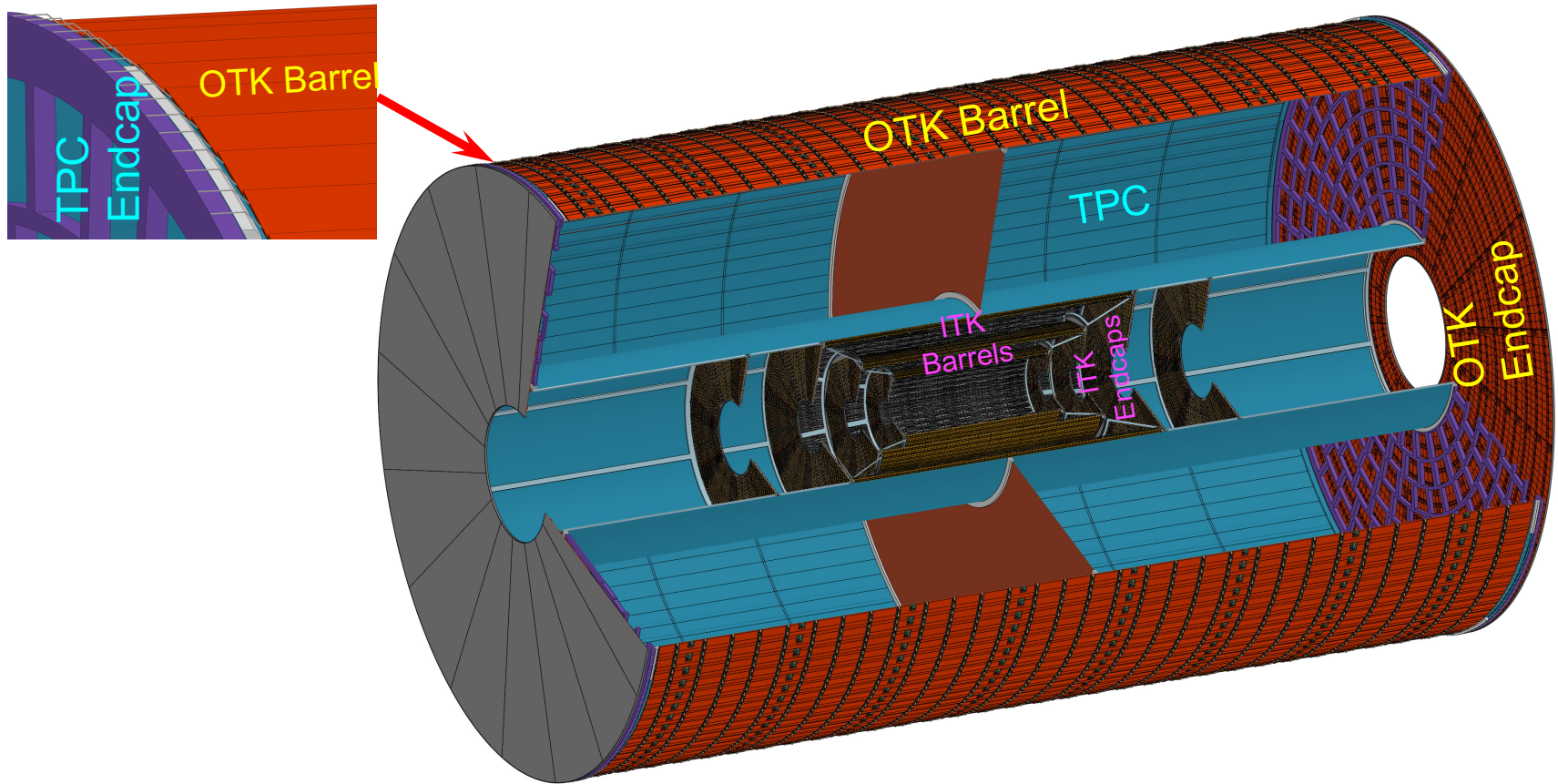


- ➔ ITK cable and pipe
- ➔ OTK cable and pipe
- ➔ ITK & OTK cable and pipe

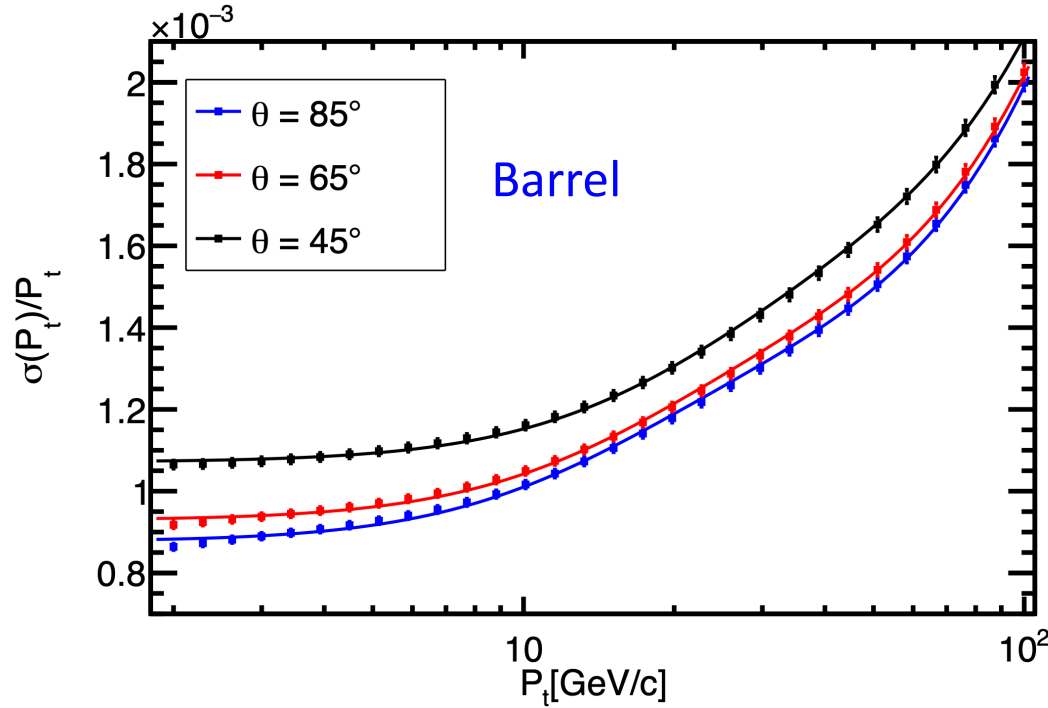
Detector	Number of power cables (supply both LV & HV)	Number of optical fibers	Number of cooling pipes
ITK Barrel	ITKB1	44	88
	ITKB2	128	128
	ITKB3	204	204
ITK Endcap (Strips)	ITKE1	128	64
	ITKE2	160	64
	ITKE3	320	64
	ITKE4	256	64
OTK Barrel	OTKB	440	220
OTK Endcap	OTKE	544	Cooling plate
Total	2,224	5,624	



CEPC Silicon Tracker



Parameterization of CEPC Tracking Performance



Qi YAN and Gang LI's formulae

Momentum resolution in the barrel region:

$$\left(\frac{\sigma_{p_t}}{p_t}\right)_{\text{Si}} = ap_t \oplus \frac{b}{\beta\sqrt{\sin\theta}}$$

$$\left(\frac{\sigma_{p_t}}{p_t}\right)_{\text{TPC}} = as_1 p_t \oplus \frac{bs_2}{\beta\sqrt{\sin\theta}}$$

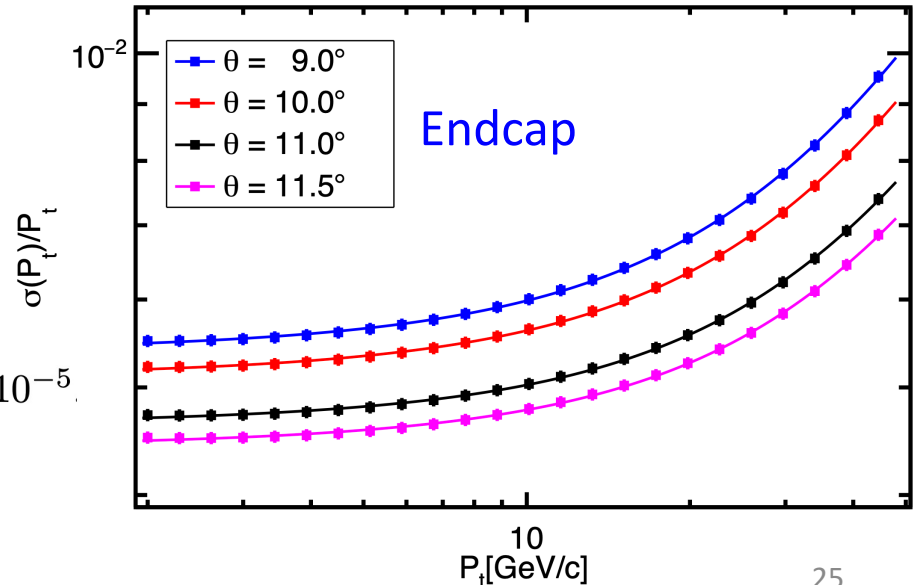
$$\left(\frac{\sigma_{p_t}}{p_t}\right)_{\text{Combined}} = \frac{1}{\sqrt{\left(\frac{\sigma_{p_t}}{p_t}\right)_{\text{Si}}^{-2} + \left(\frac{\sigma_{p_t}}{p_t}\right)_{\text{TPC}}^{-2}}}$$

where $a = 1.5 \times 10^{-5}$, $b = 1.4 \times 10^{-3}$,
 $s_1 \approx 6$, and $s_2 \approx 0.8$.

Momentum resolution in the endcap region:

$$\frac{\sigma_{p_t}}{p_t} = \frac{a' p_t}{(\tan\theta)^2} \oplus \frac{b'}{\beta \tan\theta \sqrt{\cos\theta}} \oplus \frac{c' \sqrt{p_t}}{\sqrt{\beta} (\tan\theta)^{\frac{3}{2}} (\cos\theta)^{\frac{1}{4}}}$$

where $a' \approx 0.4 \times 10^{-5}$, $b' \approx 0.9 \times 10^{-3}$, and $c' = 4.5 \times 10^{-5}$.



Progress on Silicon Tracker Ref-TRD

Chapter 5 Silicon Trackers		1
5.1	Requirements	1
5.1.1	Physics requirements	1
5.1.2	Specific requirements on Silicon Tracker	2
5.2	Overview of ITK and OTK	3
5.2.1	Technology Options and Boundary Conditions	3
5.2.2	Optimization Tools	4
5.2.3	Layout Optimization	4
5.2.3.1	The tracker length	4
5.2.3.2	Barrel Region	5
5.2.3.3	End-cap Region	6
5.2.4	Summary and discussion on tracker optimization	6
5.3	Inner silicon tracker (ITK)	7
5.3.1	CMOS chip R&D	7
5.3.1.1	HV-CMOS pixel R&D	7
5.3.1.1.1	Technology survey for silicon pixel detectors	7
5.3.1.1.2	Development of HV-CMOS pixel sensor for CEPC	8
5.3.1.1.3	COFFEE1	8
5.3.1.1.4	COFFEE2	10
5.3.1.2	CMOS strip R&D	14
5.3.2	ITK design	21
5.3.2.1	ITK barrel design	21
5.3.2.2	ITK endcap design	22
5.3.2.3	Alternative design for the ITK	26
5.3.3	Readout electronics	32
5.3.4	Mechanical and cooling design	32
5.3.4.1	Barrel local support	32
5.3.4.1.1	Materials	32
5.3.4.1.2	Structural characterisation	33
5.3.4.1.3	Thermal characterisation	34
5.3.4.2	Endcap local support for HV-CMOS pixel detector	35
5.3.4.2.1	Materials	35
5.3.4.2.2	Structural characterisation	36
5.3.4.2.3	Thermal characterisation	36
5.3.4.3	Endcap local support for CMOS strip detector	36
5.3.4.3.1	Materials	36
5.3.4.3.2	Structural characterisation	36
5.3.4.3.3	Thermal characterisation	36
5.3.5	Prospects and plan	39
5.3.5.1	Development of the CMOS pixel sensor	39
5.3.5.2	Development of the CMOS strip sensor	40
5.3.5.3	Module and system level development	41
5.4	Outer silicon tracker (OTK) with TOF	42
5.4.1	AC-LGAD sensor and ASIC R&D	42
5.4.1.1	AC-LGAD Sensor R&D	42

5.4.1.1.1	AC-LGAD simulation	43
5.4.1.1.2	Testing setup	44
5.4.1.1.3	Pixelated AC-LGAD prototypes	46
5.4.1.1.4	Strip AC-LGAD prototype and properties	48
5.4.1.2	AC-LGAD ASIC R&D	53
5.4.1.2.1	General requirements	53
5.4.1.2.2	ASIC architecture	54
5.4.1.2.3	Single-channel readout electronics	54
5.4.1.2.4	Data process and digital blocks	57
5.4.1.2.5	Prototype	58
5.4.1.2.6	Power distribution and grounding	61
5.4.1.2.7	Radiation tolerance	61
5.4.1.2.8	Monitoring	62
5.4.1.2.9	Development plan and schedule	62
5.4.2	OTK design	63
5.4.2.1	OTK barrel design	63
5.4.2.2	OTK endcap design	65
5.4.3	Readout electronics	70
5.4.3.1	Front-end board	70
5.4.3.2	Concentration, care and power distribution	71
5.4.3.3	Slow control and monitoring	71
5.4.3.4	Clock distribution	71
5.4.4	Mechanical and cooling design	72
5.4.4.1	Barrel support	72
5.4.4.1.1	Materials	73
5.4.4.1.2	Structural characterisation	74
5.4.4.1.3	Thermal characterisation	75
5.4.4.2	Endcap support	76
5.4.4.2.1	Materials	78
5.4.4.2.2	Structural characterisation	78
5.4.4.2.3	Thermal characterisation	79
5.4.5	Prospects and plan	80
5.4.5.1	Development of AC-LGAD strip sensor for CEPC	80
5.4.5.2	Development of AC-LGAD readout ASIC	80
5.4.5.3	Development of mechanical and cooling system	81
5.4.5.4	Summary	81
5.5	Beam background estimation	82
5.5.1	Beam background simulation	82
5.5.1.1	Pair production background	82
5.5.1.2	Single beam background	82
5.5.1.2.1	Beam Thermal Photon Scattering (BTH)	82
5.5.1.2.2	Beam Gas Coulomb Scattering (BGC) and Beam Gas Bremsstrahlung Scattering (BGB)	82
5.5.1.2.3	Touschek Scattering (TSC)	83
5.5.2	Hit rate estimation for beam background	83
5.5.3	ITK tolerable hit rate	83
5.5.4	OTK tolerable hit rate	84
5.6	Performance	86
5.6.1	The performance of the barrel region	86
5.6.1.1	Momentum resolution	86
5.6.1.2	Roles of gaseous and silicon trackers	86
5.6.1.3	Particle identification performance	87
5.6.2	The performance of the forward region (endcap)	88
5.6.2.1	Momentum resolution performance	88
5.6.2.2	Particle identification performance	90

>90% of the content has been completed,
 with the full chapter nearing 100 pages.

撰写负责人: 李刚、严琪

撰写负责人: 赵梅

撰写负责人: 严雄波

撰写负责人: 严琪

撰写负责人: 严雄波

撰写负责人: 严琪

撰写负责人: 严琪

撰写负责人: 严琪

撰写负责人: 赵梅、严雄波、严琪

撰写负责人: 李一鸣

史欣、严琪

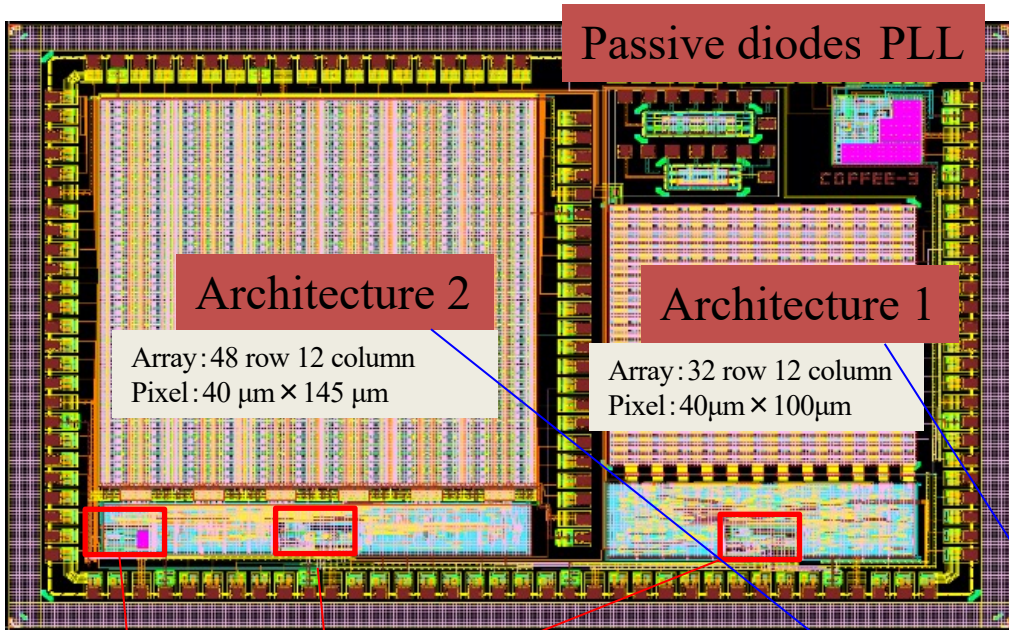
撰写负责人: 严琪

撰写负责人: 赵梅

Progress on COFFEE3 Development and Submission

Submitted 2025.1/ expected received 2025.5

Provided by Yang ZHOU



Two readout architectures:

Both include nearly a complete ASIC readout framework, and the solution can be extended to a full-size chip.

Each pixel can independently adjust its threshold through SPI (4-bit in-pixel DAC) and configure the mask.

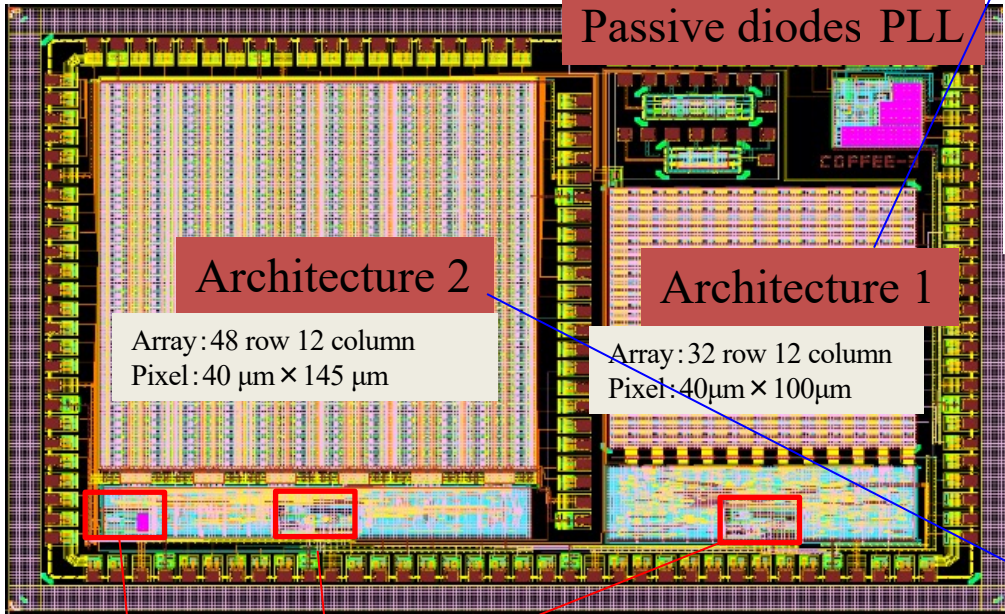
- **Architecture 1:** the optimized design framework based on current process conditions (Triple-well process);
- **Architecture 2:** an improved solution, while requires process modification. (Deep P-well required); fully utilize the advantages of the 55nm process node,

- In-pixel electronics;
- Pix matrix readout strategy;
- Periphery digital logics and functional IPs;
- Slow control & Fast control....
- Data/Power/CLK interfaces.....

.....

Provided by Yang ZHOU

COFFEE3 architecture 2:



Architecture 2

Array: 48 row 12 column
Pixel: 40 μm \times 145 μm

Passive diodes PLL

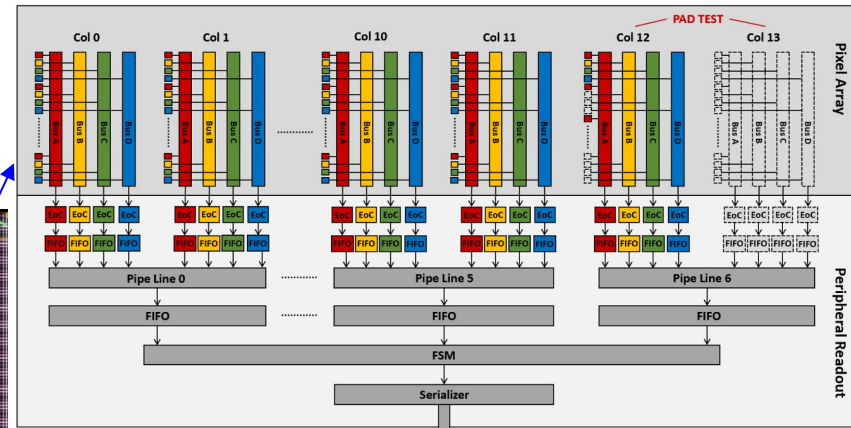
Architecture 1

Array: 32 row 12 column
Pixel: 40 μm \times 100 μm

DLL

LVDS driver/receiver up to 1.28Gb/s

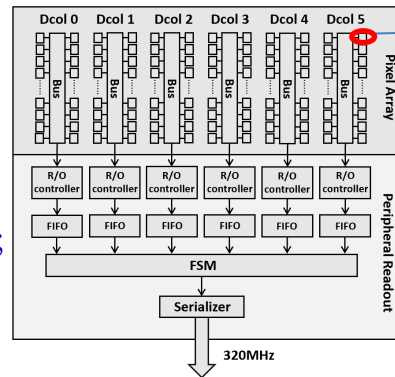
Architecture 1: NMOS Pixel Array Schematic Diagram



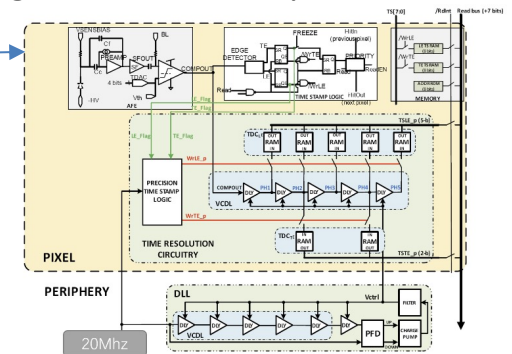
LVDS driver/receiver up to 1.28Gb/s

- In-pixel NMOS based comparator, in-pixel 4-bit DAC for threshold tuning;
- Time information (TOA, TOT...) and data formation in the end of each column;
- Improved capability to manage high incident conditions;

Architecture 2: an improved solution, fully utilize the advantages of the 55 nm process node



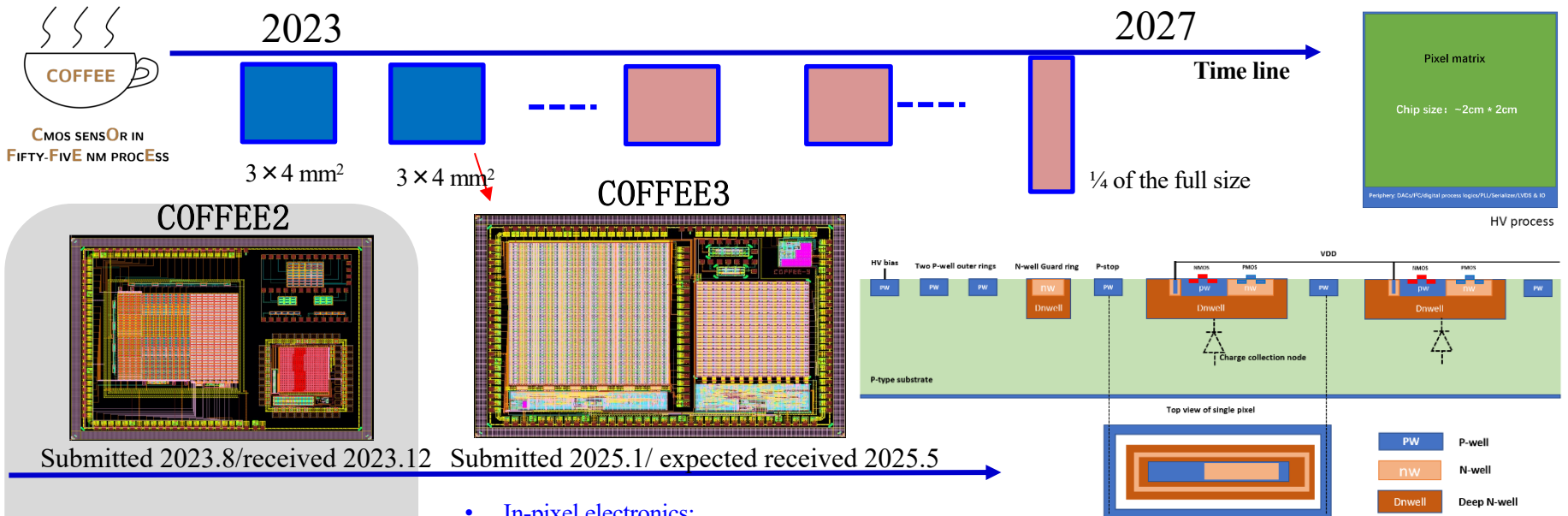
LVDS driver/receiver up to 1.28Gb/s



- In-pixel Coarse-fine TDC and 4-bit threshold tuning;
- ToA and ToT information are saved in each pixel;
- Data-driven readout;

Prototypes in 55 nm HV-CMOS Process

Several MPWs to reach the full-size full-function sensor



Process characteristics & Technology validation

- In-pixel electronics;
- Pix matrix readout strategy;
- Periphery digital logics and functional IPs;
- Slow control & Fast control....
- Data/Power/CLK interfaces.....

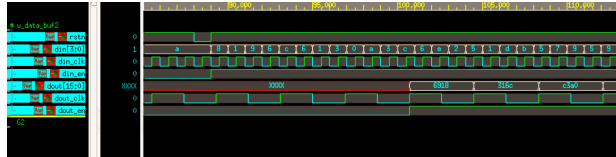
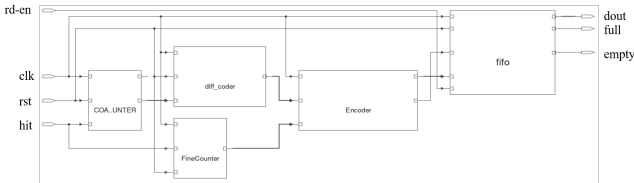
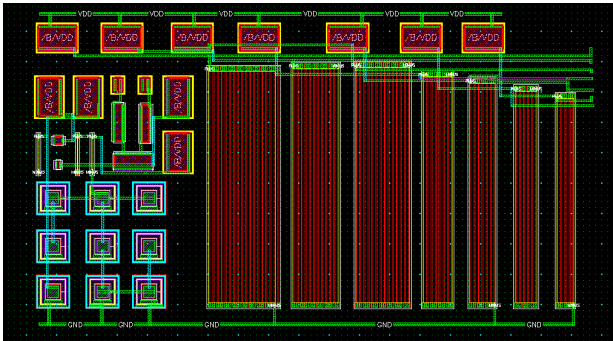
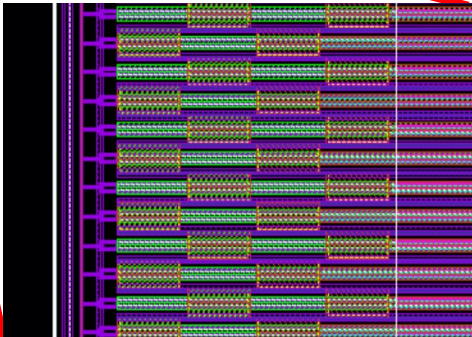
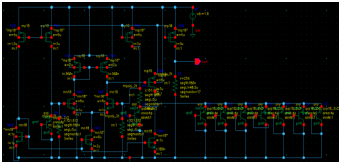
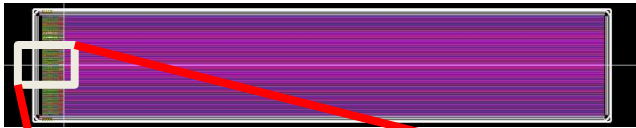
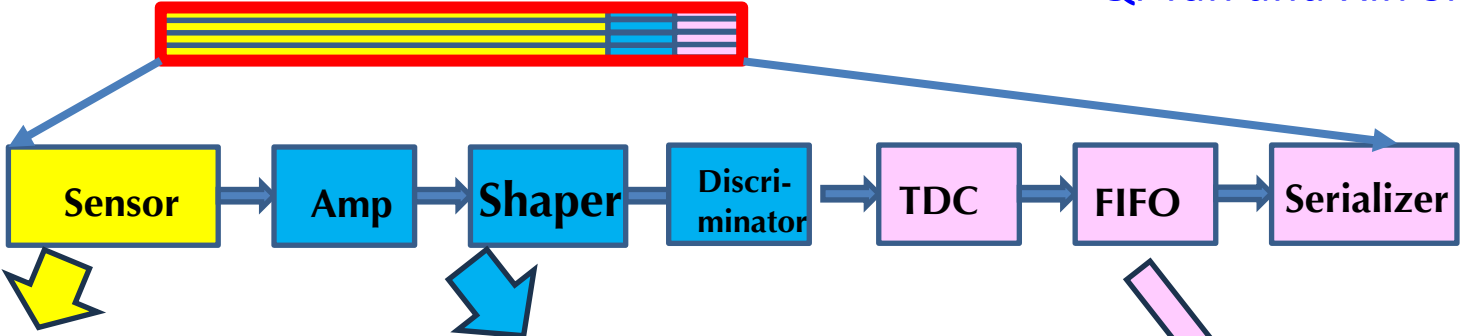
COFFEE3芯片设计团队: 15 designers

- 高能所: 李乐怡 (山东大学/高能所)、张晓旭 (南京大学/高能所)、赵梅、陆卫国、周扬;
- 西北工业大学: 吴慧敏、赵泽焯、赵宇、魏政、魏晓敏;
- 浙江大学: 邓建鹏、李鹏戌;
- 大连民族大学: 陈洋、王雨韵、施展;

Progress on CMOS Strip Chip (CSC1) Development

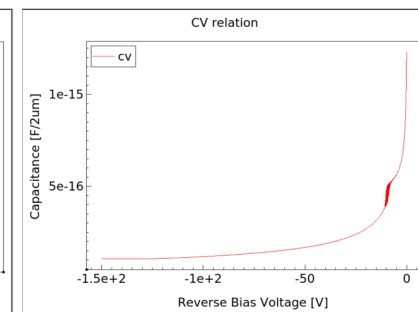
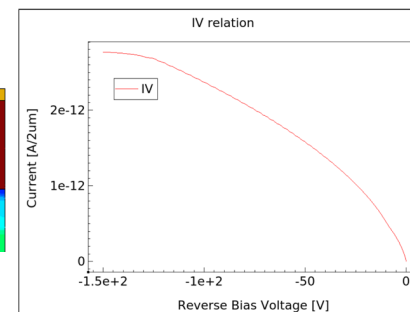
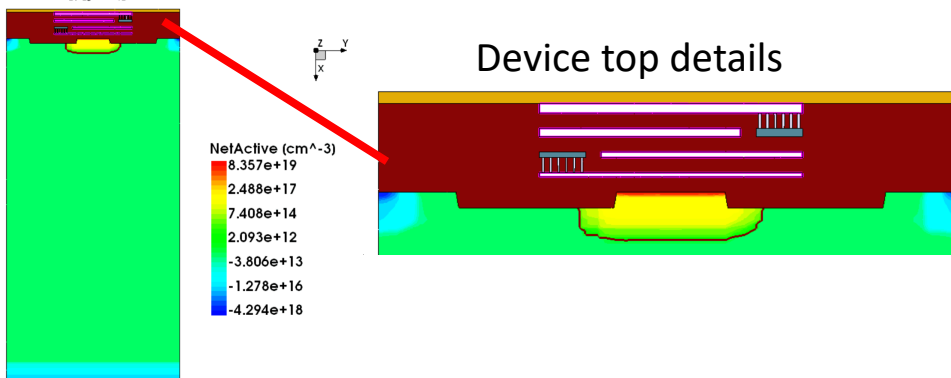
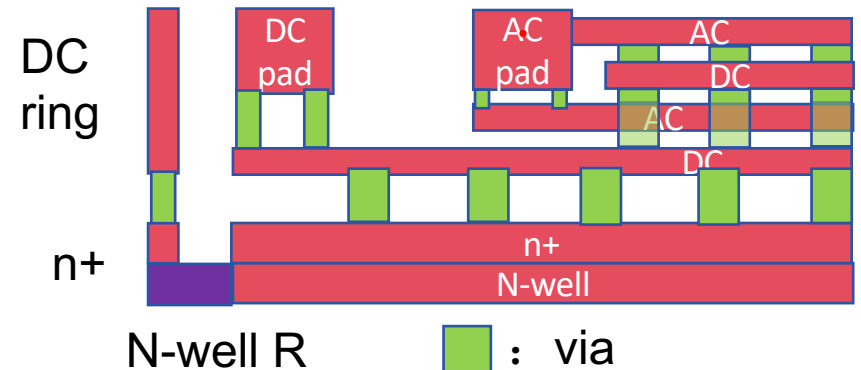
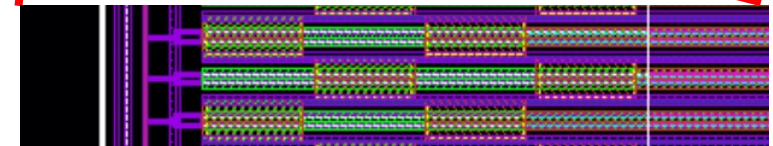
Qi Yan and Xin Shi

CSC1 Sensor + ASIC



CMOS Strip Sensor Design and Simulation

- Foundry: CSMC CMOS (1P4M)
- Sensor Size: 20.000 mm × 3.486 mm
- Strip length: 19.716 mm, pitch 75.5 μm
 - n-well: 18 μm, n+: 15 μm
 - p-well: 4 μm, p+: 2 μm
- pad area: 75 μm × 180 μm
- Number of channels: 40
- n-well to bias ring via well-resister
- Two n+ guard rings
- Doping concentration

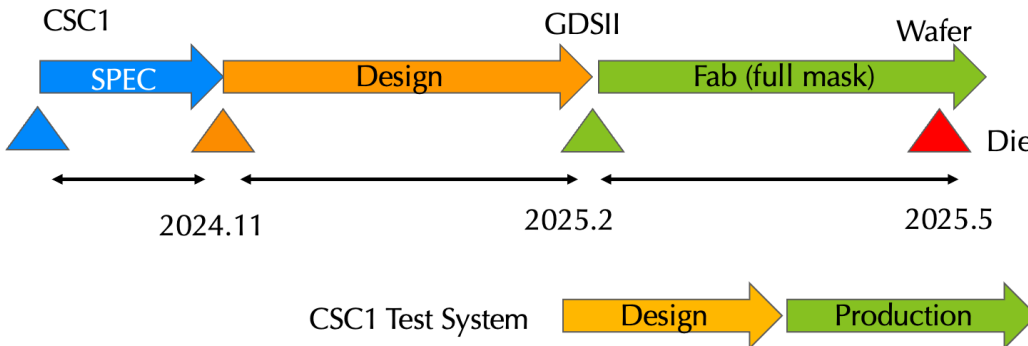
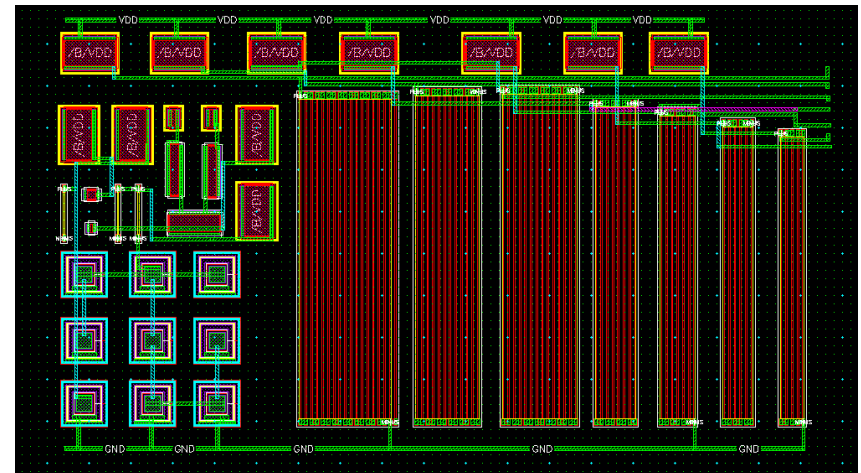
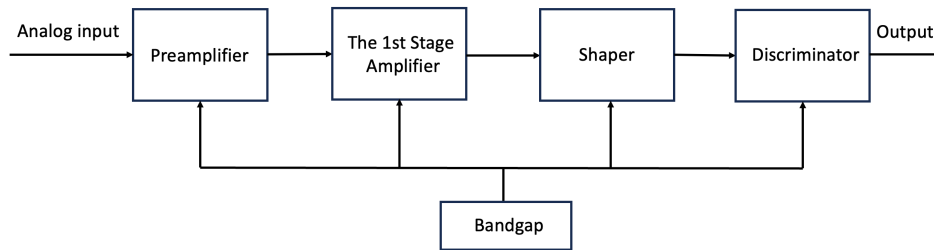


IV/CV results consistent with existing data*

* Diehl et. al, Characterization of passive CMOS strip sensors, NIMA 1033 (2022) 166671

Analog Frontend Design Status and CSC1 Submission

- Completed the design of Analog Frontend (AFE): Preamplifier, the 1st stage amplifier, shaper, discriminator, and bandgap.
 - Circuit design, layout design, pre-simulation, and post-simulation
- Completed the overall Design Rule Checking (DRC), Layout Versus Schematics (LVS) checks.



CSC1

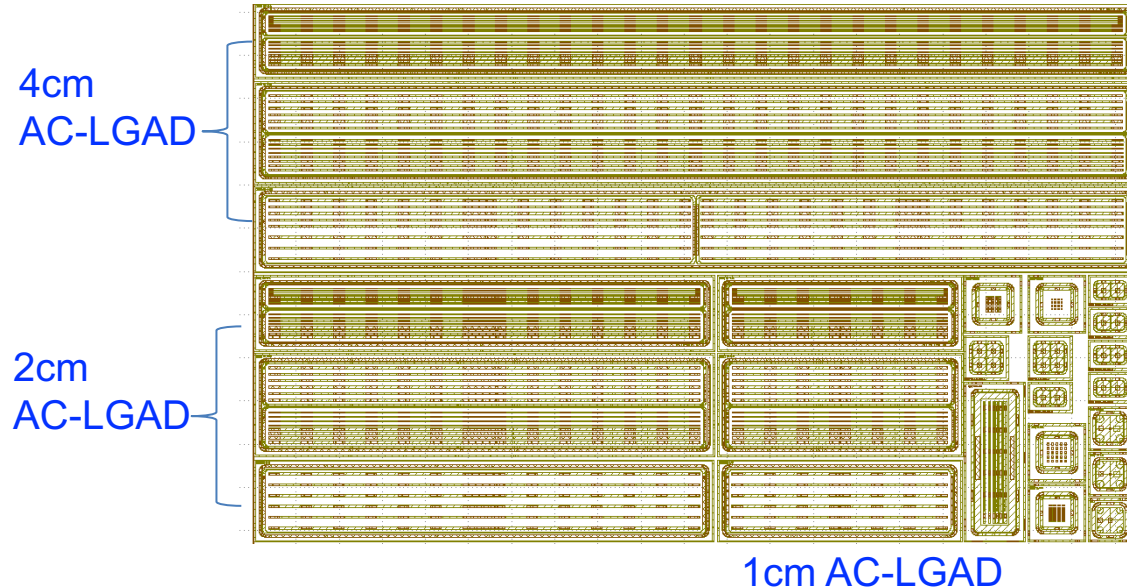
- Working on the TDC
- Target for submission by February

AC-LGAD Strip Sensor New R&D Design

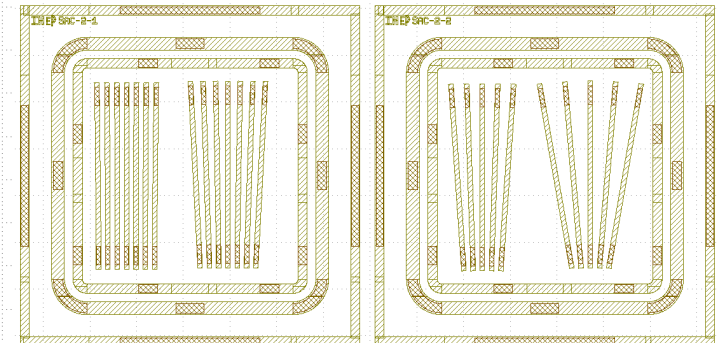
New layout and design was done based on simulation. IHEP new AC-LGAD strip sensor prototype design for the CEPC OTK&TOF:

- Strip length: 1 cm, 2 cm, and 4 cm
- Strip pitch size: 100 μm , 200 μm , and 500 μm
- Optimized isolated structure design to reduce sensor capacitance
- Process design optimized for better spatial resolution (n+ layer dose)

Designed by Mei Zhao



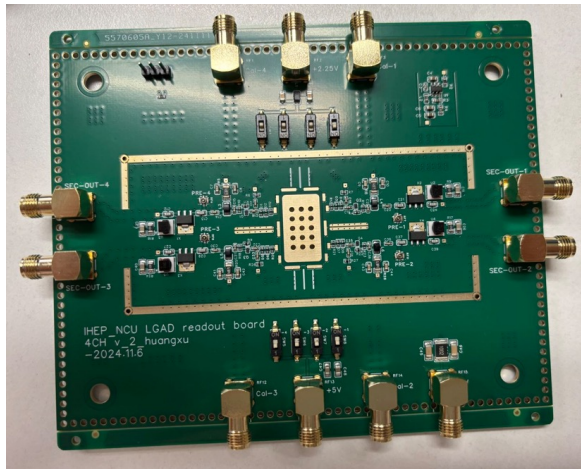
Sector shape AC-LGAD for endcap



AC-LGAD Sensor Readout Board Preparation

Mei Zhao

- 4-channels readout boards has been fabricated for AC-LGAD testing
- 2-stage amplifiers, Gain \sim 70
- Signal shape has significantly improved, showing no oscillations.



AC-LGAD Strip Sensor Development Plan

Short term plan: 2024.12-2025.2

Simulation: ongoing

- Simulation of Strip length and its effect (signal shape)
- Simulation to reduce capacitance (isolation structure)
- Simulation of process parameters to optimize spatial resolution (AC coupling capacitor, n+ dose)

Testing:

- Multi-channel readout board with low noise design and fabrication (2 stages of amplifier) **done**
- Testing of short strip connected, radiation testing(TID) **ongoing**

Submission 1: 2025.2 (layout design is done, process simulation ongoing)

Strip AC-LGAD with different length and pad-pitch size: [1 cm, 2 cm, 4 cm] [100um, 200 um, 500 um]

- Strip AC-LGAD with different process parameters: n+ dose, dielectric material and thickness, ...
- Strip AC-LGAD with different isolation structure →Capacitance
- Sensors with EPI layer of different thickness (50 um, 65 um, 80 um, 300 um)

Sensor Testing:

- clarify the sensors performance and requirement (include test beam and radiation test)
- Find out how to optimize the sensor performance (structure and process)

Submission 2: 2025.10

- Based on the results from first version and more simulation
- Sensors with strip length ~4cm

Sensor Testing: basic properties and test together with ASIC and BEE

Submission 3: 2026.6

- large area sensor design and fabrication

Submission 4 if needed: 2027.2

- module: built sensor + ASIC module and test

OTK AC-LGAD Readout ASIC (JuLoong, 烛龙)

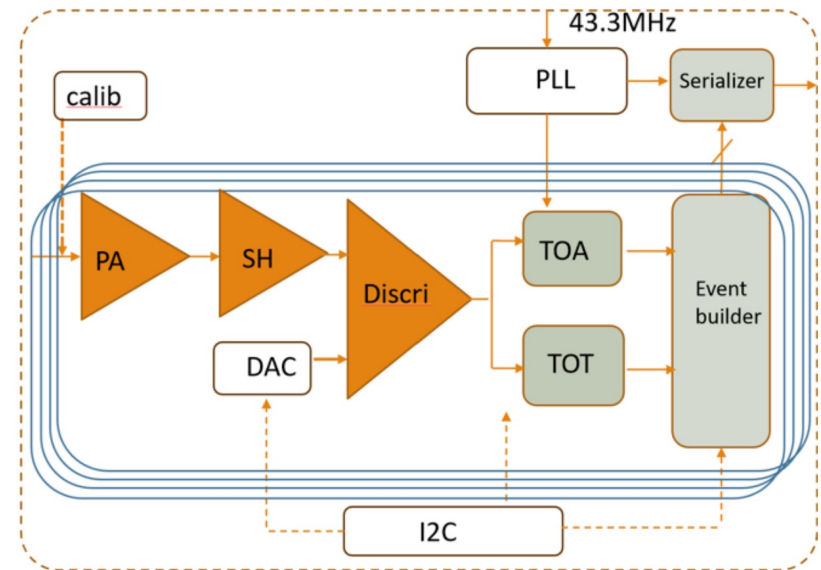
Xiongbo YAN

➤ Functions:

- TOA (Time of arrival) for precise time and TOT (Time over threshold) for time walk correction and accurate position determination.
- Each channel includes preamplifier, discriminator, and Time-to-Digital Converter (TDC).

➤ Requirements:

- 128 channels, channel pitch less than 100 μm .
- Single channel power consumption less than 20 mW.
- Time resolution for TOA better than 30 ps.



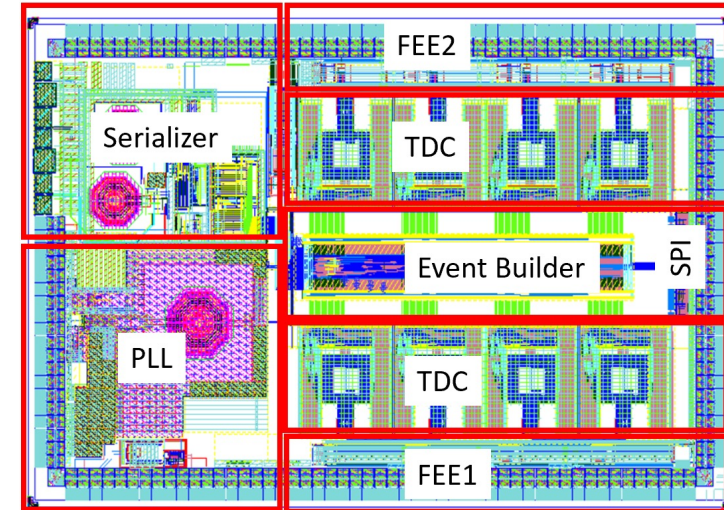
JuLoong diagram

OTK AC-LGAD ASIC Development Progress

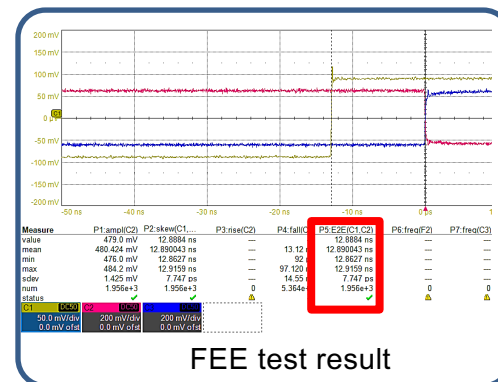
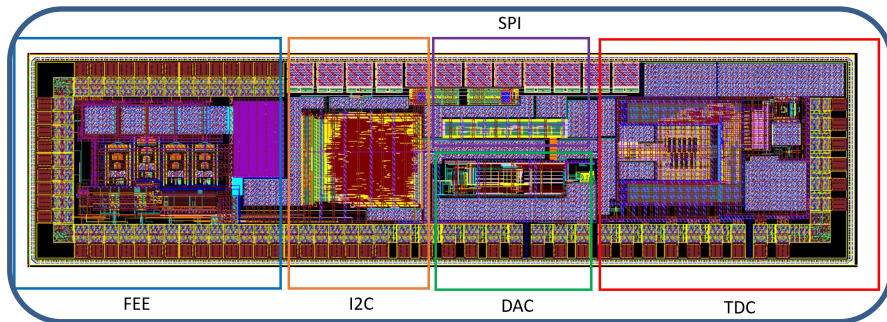
Xiongbo YAN

Several key cells are designed or verified:

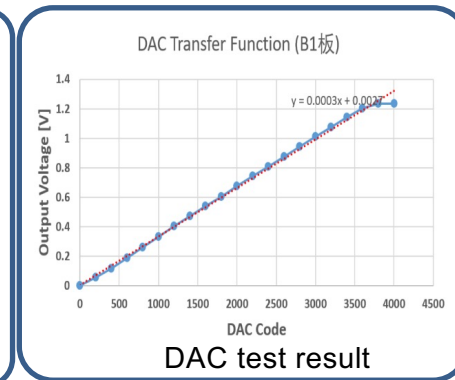
- FPMROC (10 ps) chip
 - FEE: Preamplifier+Discriminator
 - jitter < 7.8ps @ input 2.5mV, $t_r = 0.1ns$, $C_s = 0 pF$
(need to be test with real LGAD sensor)
 - TDC core needs a new design
 - PLL, Serializer, SPI is verified but need to be simplified
- I2C Slave: ASIC parameter configuration
- 12-bit DAC: threshold and calibration



FPMROC



FEE test result

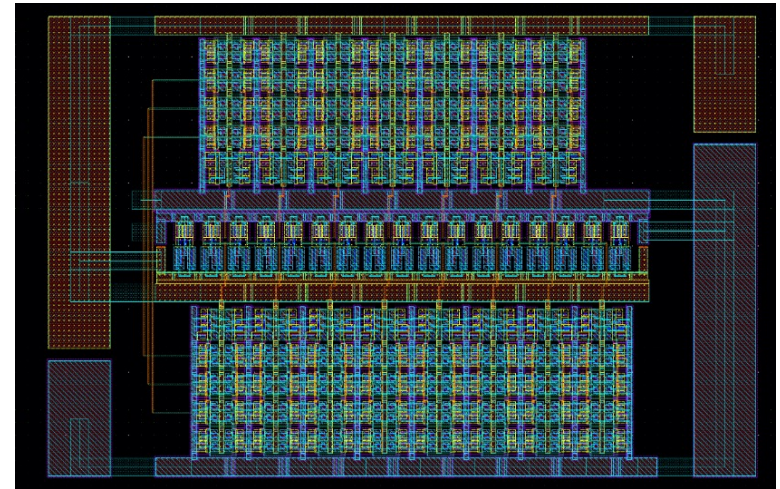


DAC test result

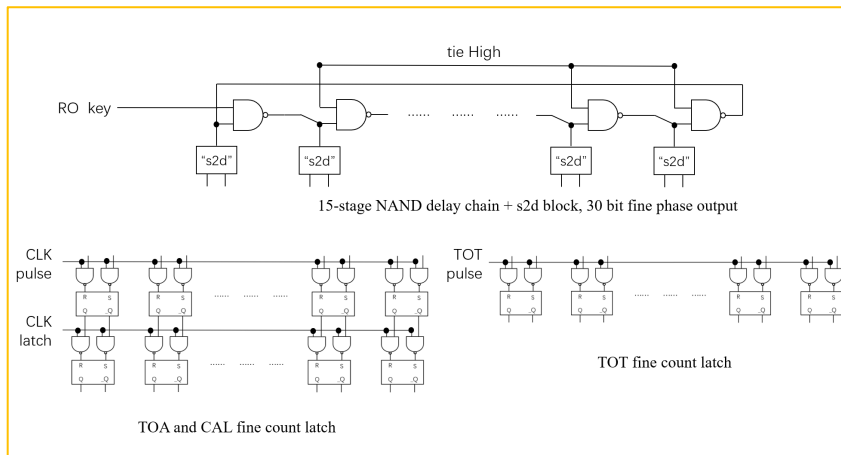
OTK AC-LGAD TDC Core Design

Xiongbo YAN

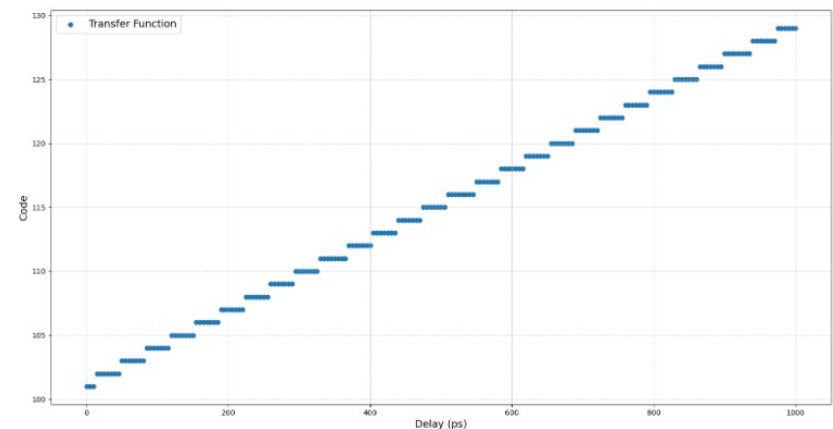
- Event driven delay line to reduce the power
- Real time Calibration for PVT (Process, Voltage, Temperature)
- LSB ~ 36 ps for preliminary layout post-simulation
- Power Consumption :
 - Average current for single event: $443 \mu\text{A}$
 - Static current: $< 5 \mu\text{A}$



Delay line layout



Single-Channel Delay Chain and Quantization Block Diagram



TOA transfer function curve (step=5 ps, TT27)

OTK AC-LGAD ASIC (JuLoong) Development Plan

- 2025.4: Design key components, including preamplifier, discriminator, and TDC, along with the design of the ASIC test system. Performance testing of the ASIC will be conducted by the end of the year, with radiation hardness testing for each component.
- 2025.7: Conduct components performance test.
- 2025.10: Refine components and complete the first version of multi-channel integration.
- 2026. 2: Performance test on the multi-channel ASIC, including radiation hardness testing.
- 2026. 6: Further refinement and integration of 128 channels.
- 2027.10: Performance testing of 128 channel ASIC will be conducted, integrated with LGAD sensor.
- 2027.12: Finalize the prototype and prepare for mass production of the chips.

Summary

- Our silicon tracker group is steadily progressing towards the Ref-TDR.
- We greatly appreciate the mechanical and thermal support from Xuedong Wu and his group at Zhengzhou University of Light Industry (郑州轻工业大学).
- After the Ref-TDR, we will focus on R&D efforts, including all sensor technologies and the supporting components, such as mechanical and thermal R&D.
- In parallel, I, along with the group members, will make significant efforts to strengthen our connections with research units and industries, including semiconductor foundries, to advance the R&D work.

5.4.5.4 Summary

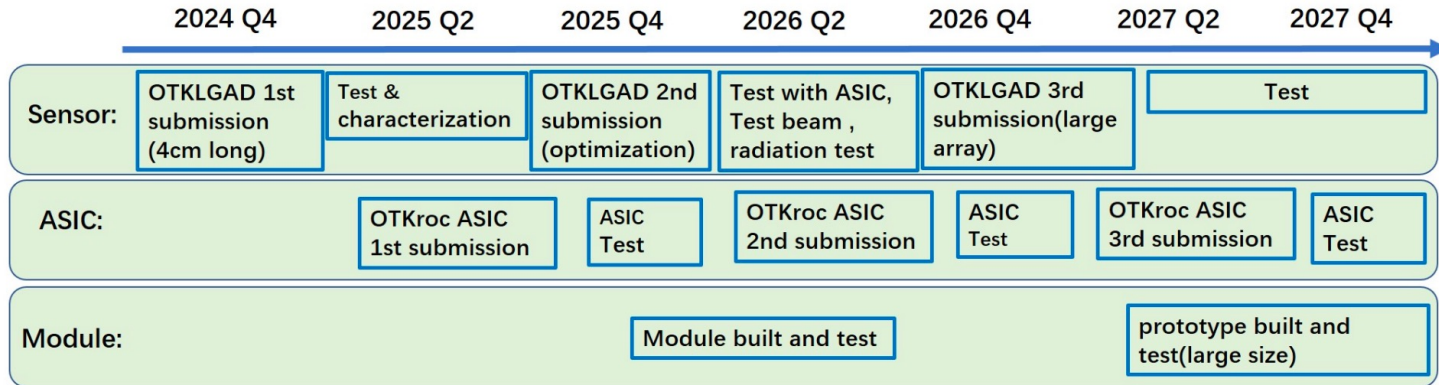


Figure 5.106: Timeline for OTK, including sensor, ASIC, mechanics and so on

All the R&D mentioned above is part of a 3-year plan, as detailed in Fig. 5.106. Considering the project timeline of more than 5 years from construction, the CEPC project is flexible enough to adjust its technical approach and has sufficient backup plans for the engineering phase. For example, if the performance of the AC-LGAD strip sensor degrades significantly for large-dimension strip sensor, we may consider using conventional large-dimension sensor, with or without an external time-of-flight detector, or opt for bump bonding or monolithic AC-LGAD technology if it becomes mature.

For the OTK system, including sensor, readout ASIC, and mechanical and cooling components, we are open to both domestic collaborations with research units and industry as well as international partnerships. In light of all these factors, we are confident in delivering a high performance OTK system that meets the physics requirements in a timely manner.